

Single crystal scintillators – preparation technologies

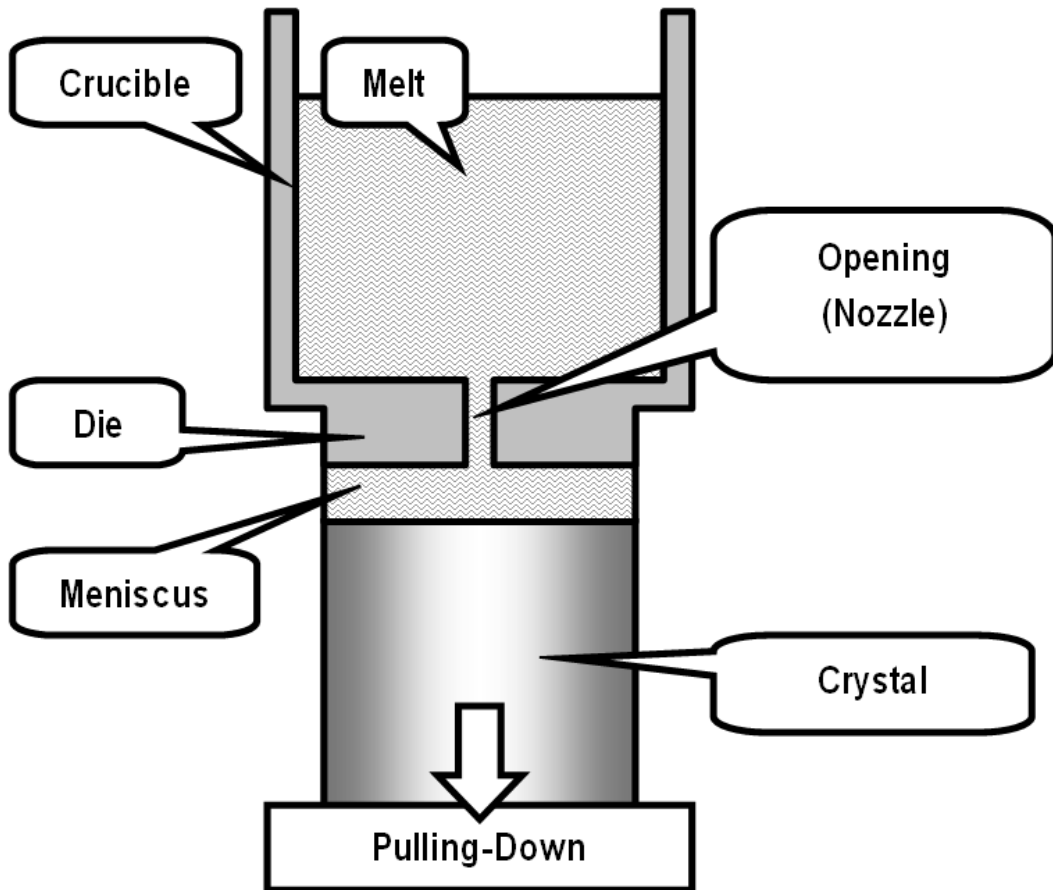
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Principle of micro-pulling-down (mPD) method

Growth of small crystals (few mm diameter, few mm-cm length), fast growth rate (0.01-10 mm/min), ideal for material composition screening



Modern mPD setup developed around 1992-1993 in Tohoku University, Sendai, Japan, to grow LiNbO_3 and related materials

Micro-capillary for fiber crystal growth + pulling down

Resistive heating, inductive (radiofrequency) heating, possible application of active afterheater

Melt flows out due to gravity, hydrostatic pressure – possibility to grow from non-wetting melts – possibility of shaped crystal growth for wetting melts due to capillary action

Device-sized crystals, no machining losses

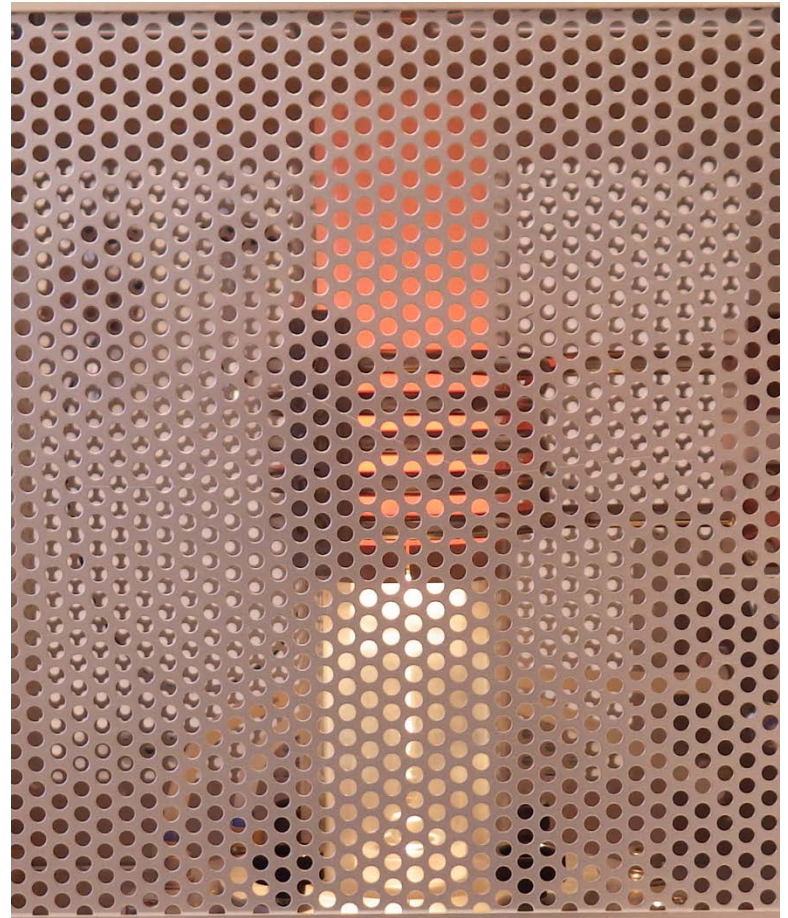
Micro-pulling-down method

Oxide crystals


Micro-pulling-down (mPD) setup

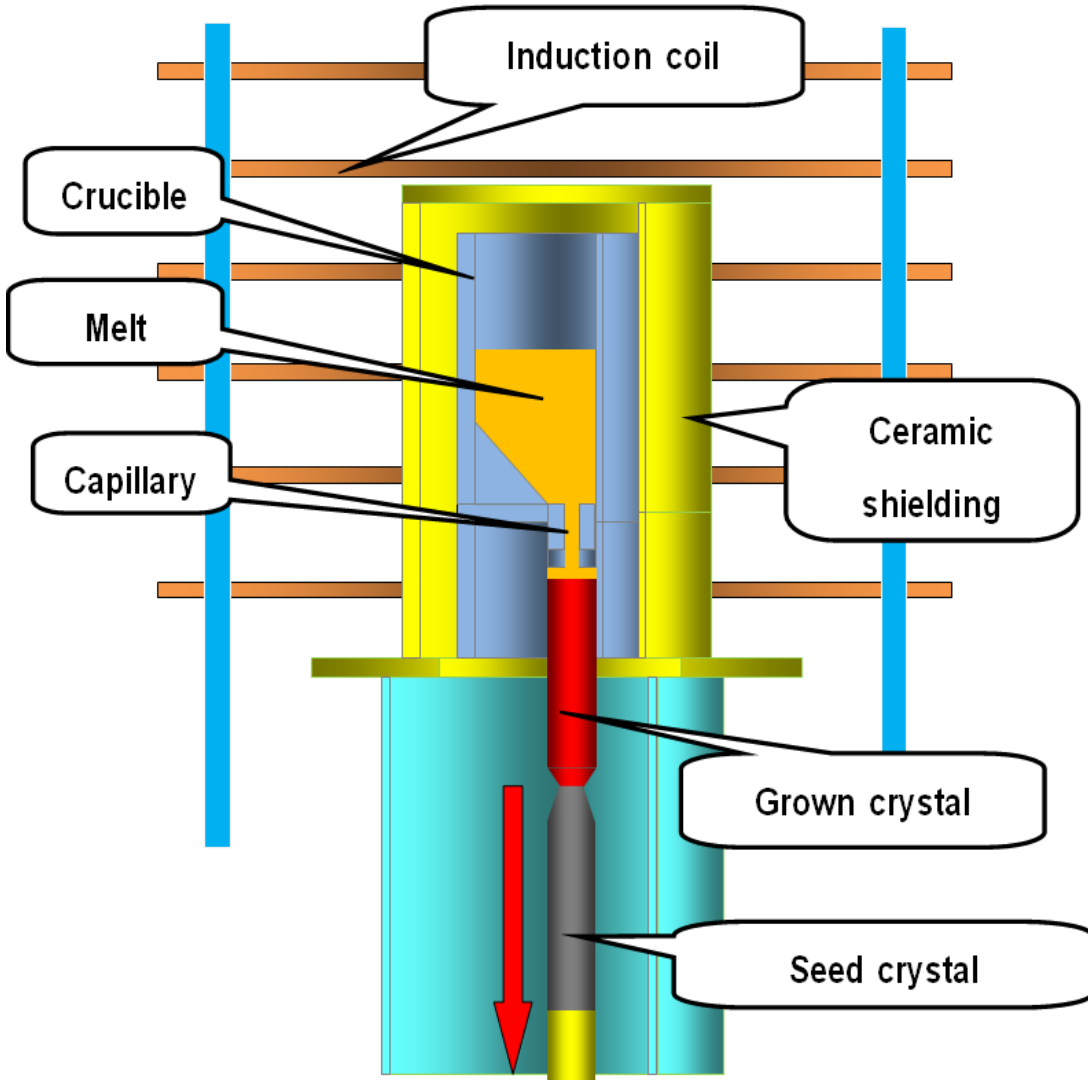
*Institute of Physics, Czech
Academy of Sciences, Prague,
Installed in June 2015*

*Type T-MPD-OX
by Akita Seiko Co., Ltd. Japan*



Crystal growth by mPD method

Gas flow 



RF heating

Atmosphere: N₂, Ar
Flow-through system

Flow

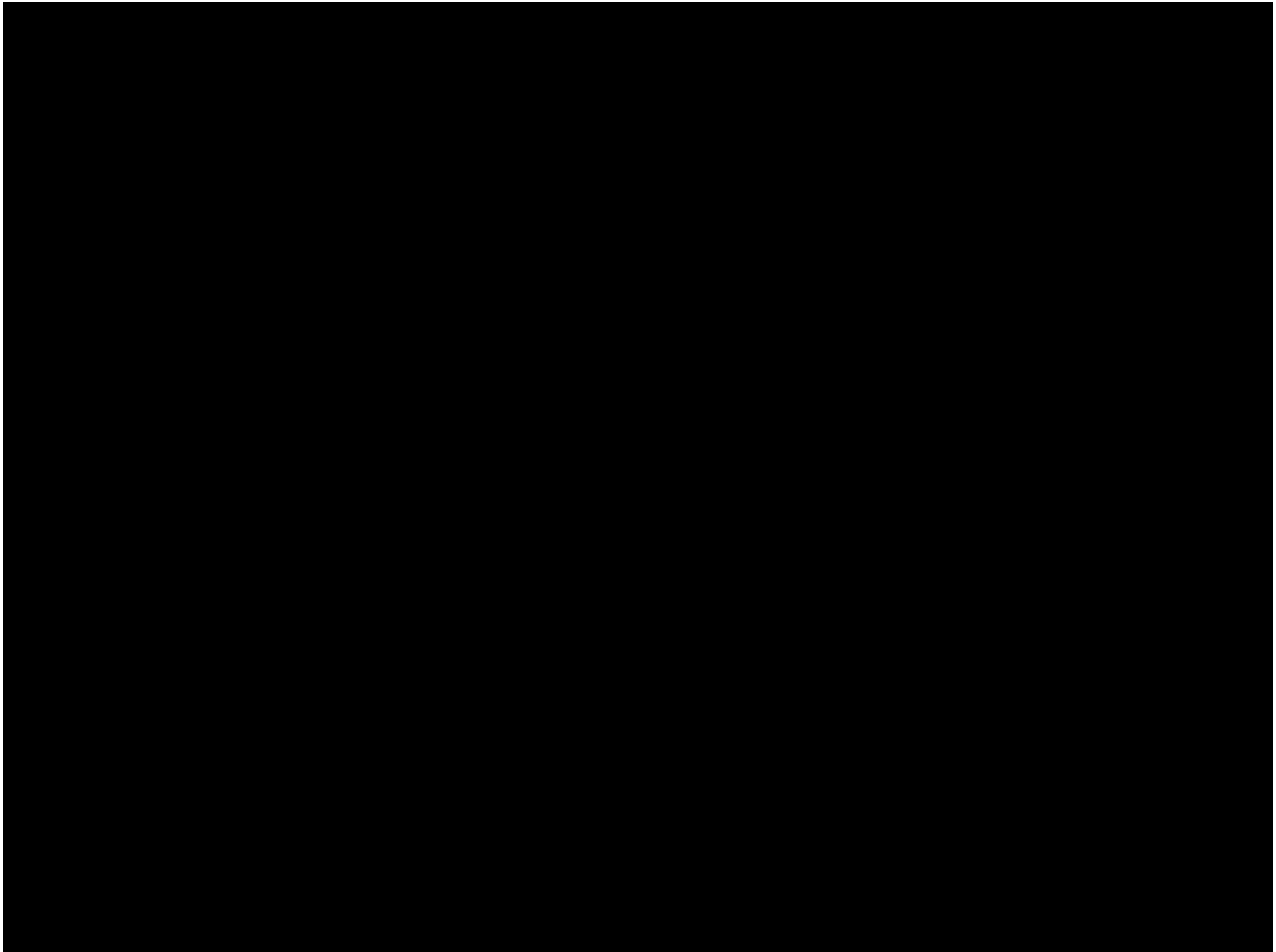
upwards/downwards
(influence on
temperature gradient)

Pulling speed: 0.01-1.5
mm/min

**Monitoring with a CCD
camera** through hole in
the shielding and
afterheater

Crystal growth by mPD setup – $\text{Al}_2\text{O}_3:\text{Cr}0.1\%$

Monitoring by a CCD camera



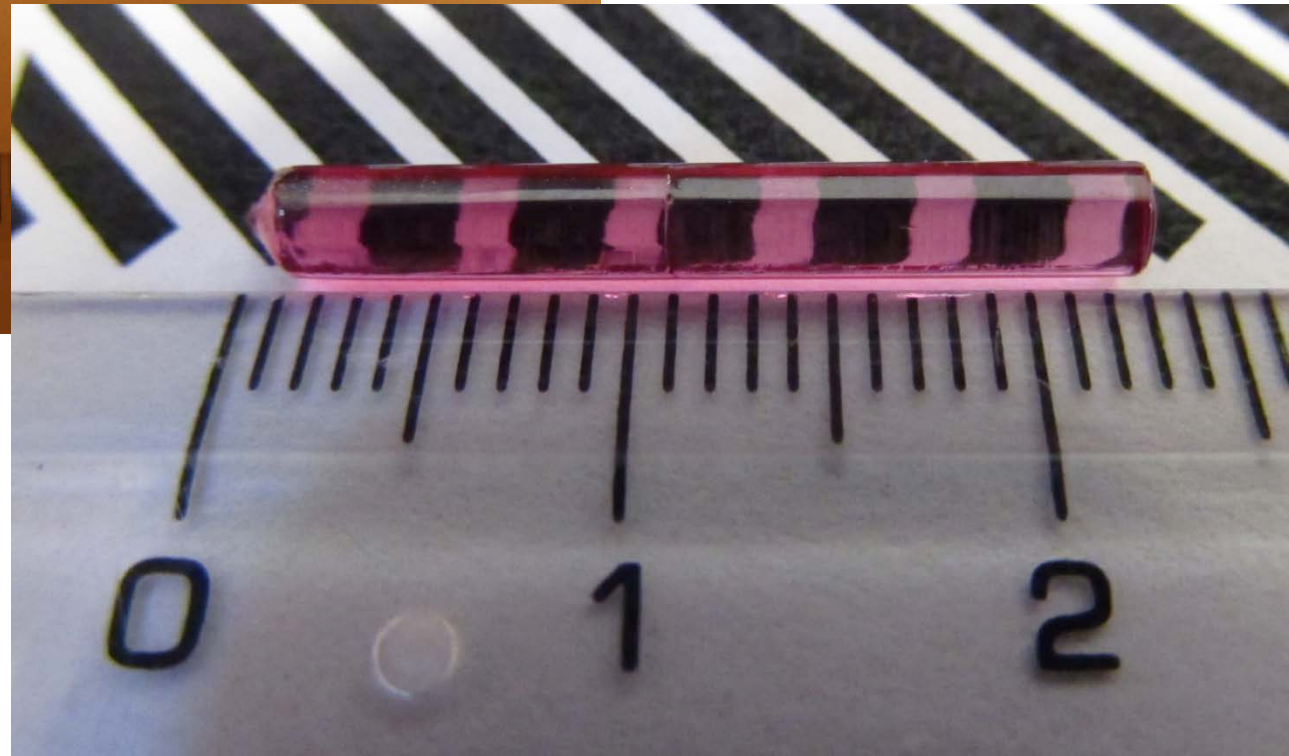
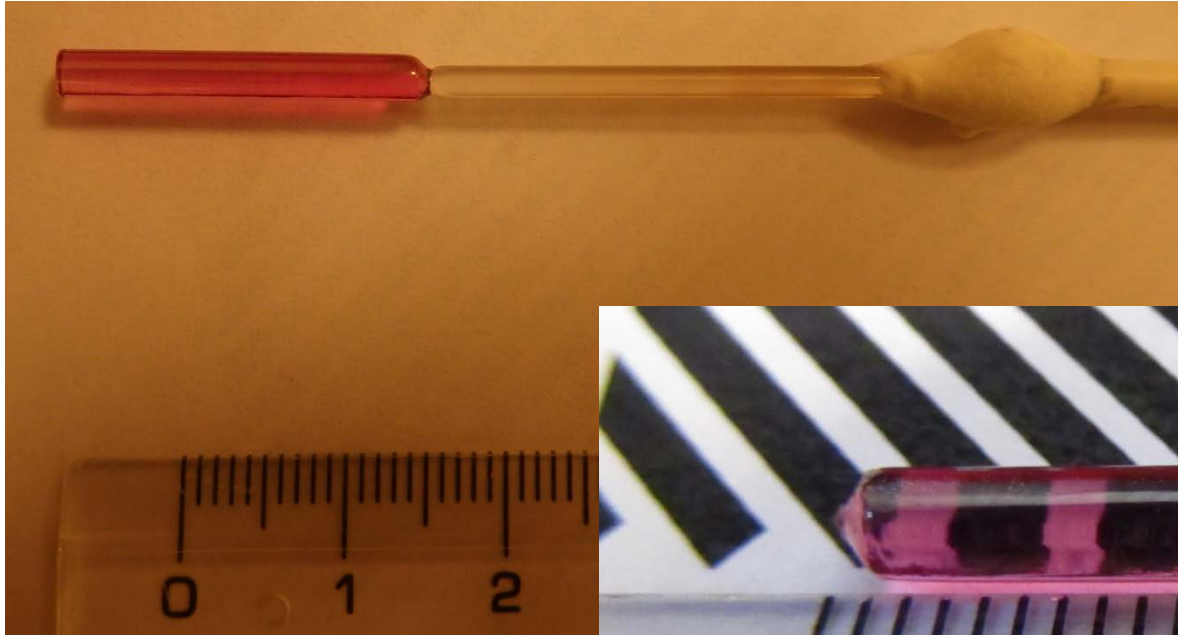
Crystal growth by mPD setup

Grown crystals ($\text{Al}_2\text{O}_3:\text{Cr}0.1\%$)

Growth time: 2.5 hours

Total experimental time: cca 7h

Rapid composition screening

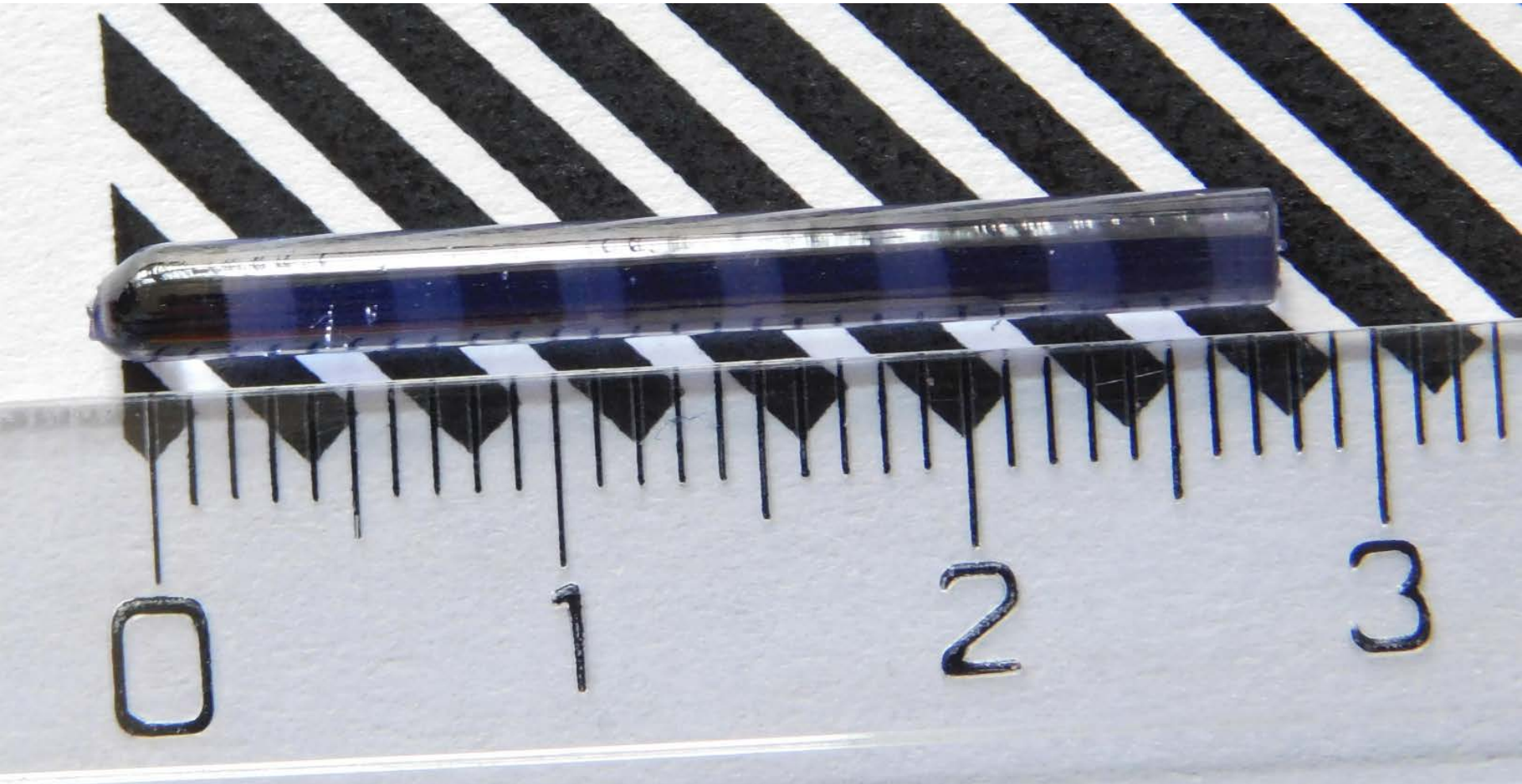


Crystal growth by mPD setup

Grown crystals

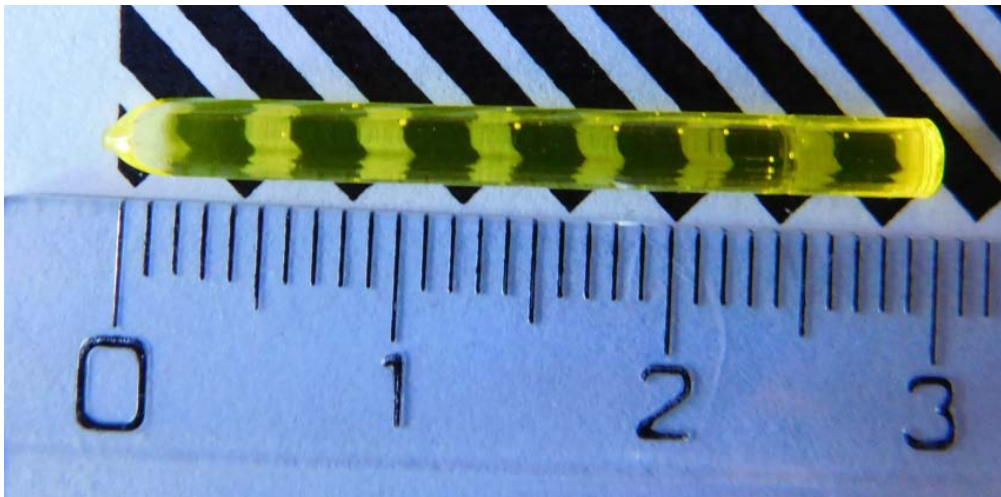
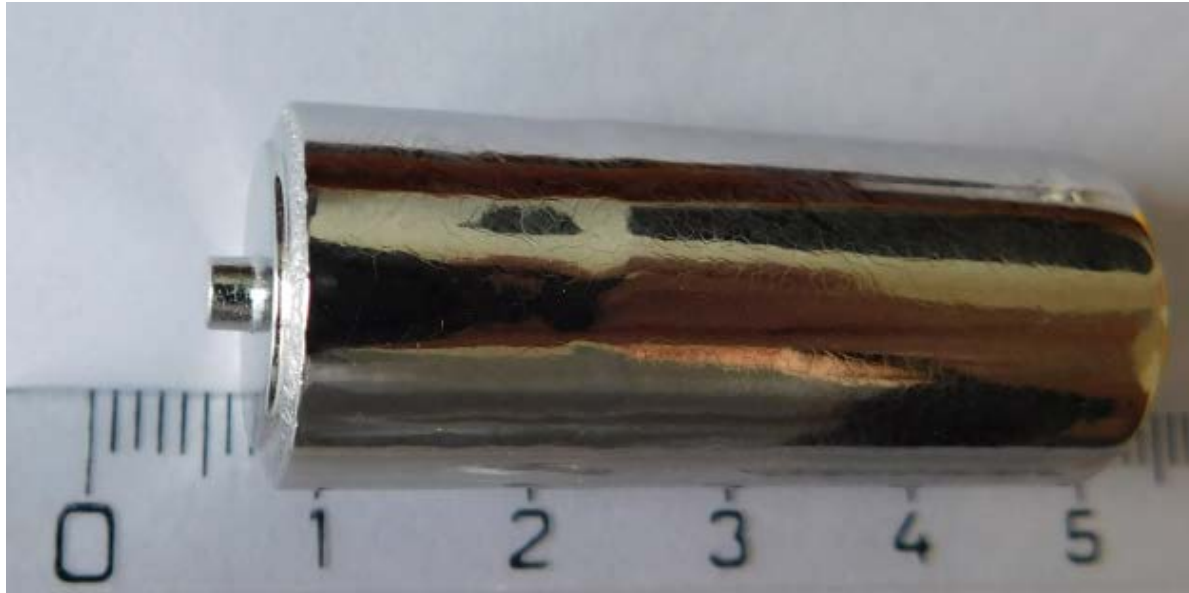
($\text{Al}_2\text{O}_3:\text{Fe}0.1\%\text{Ti}0.1\%$)

Blue sapphire



Crystal growth by mPD setup

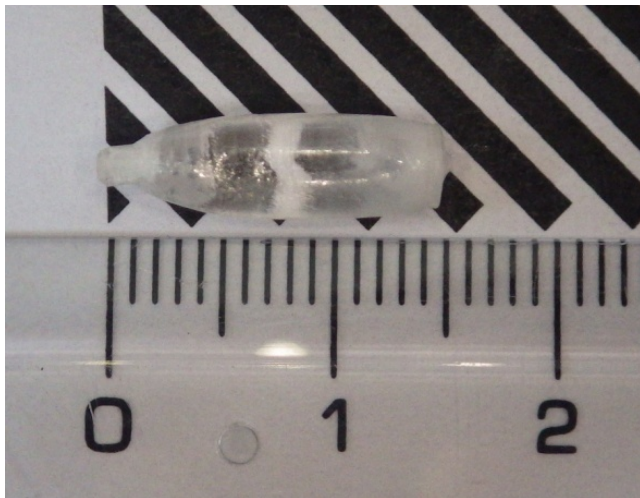
Iridium crucible with 3 mm die, 1 capillary



Grown crystal of YAG:Ce

Crystal growth by mPD setup

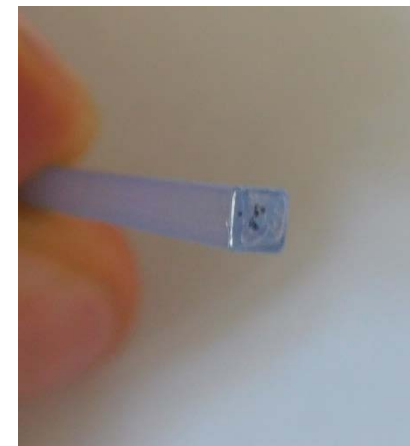
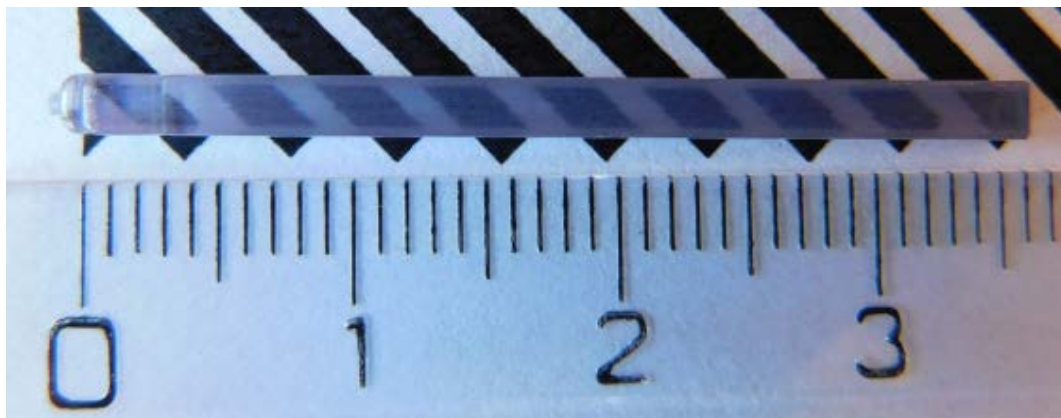
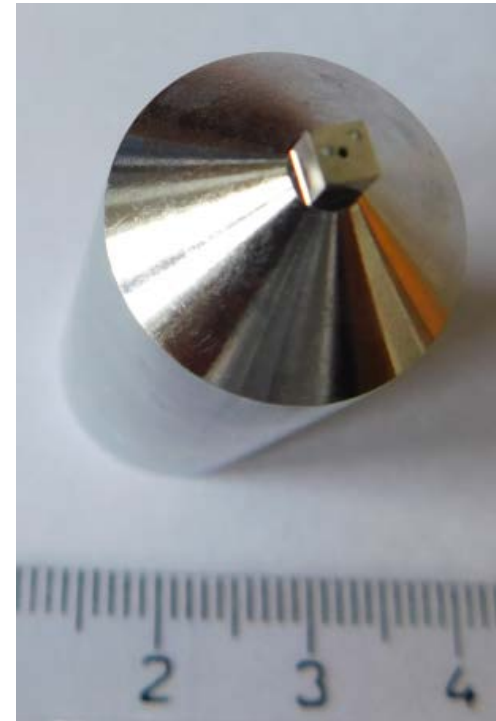
Iridium crucible with 5 mm die, 5 capillaries



Grown crystal of undoped YAP

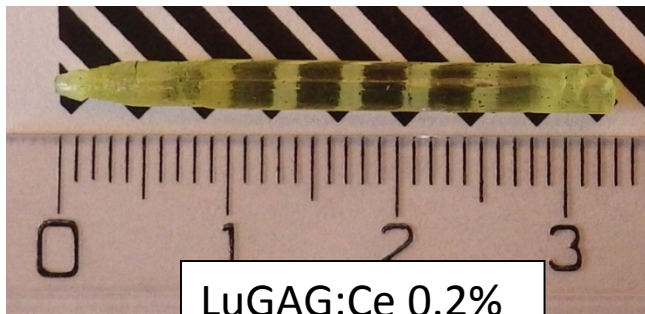
Crystal growth by mPD setup

*Iridium crucible with 2x2 mm **square** die, 1 capillary*

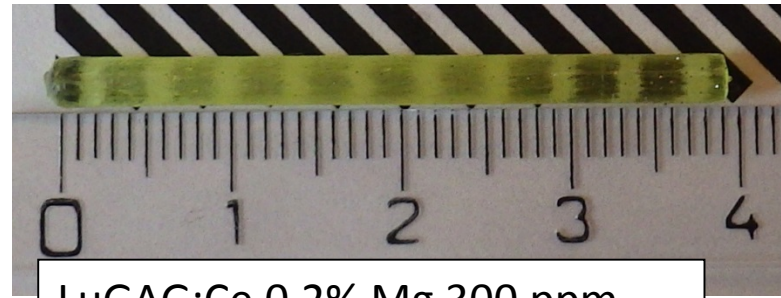


Grown **shaped crystal** of $\text{Al}_2\text{O}_3:\text{Ti}0.1\%$

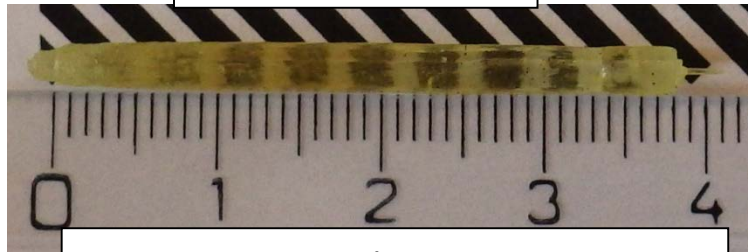
Lu₃Ga₃Al₂O₁₂ (LuGAG) - Grown crystals



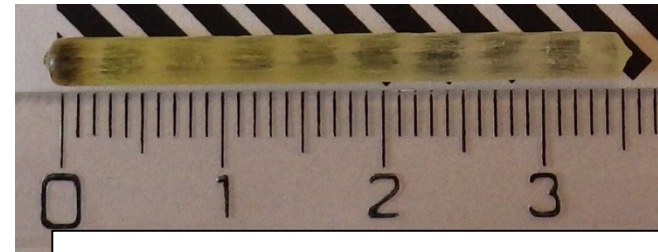
LuGAG:Ce 0.2%



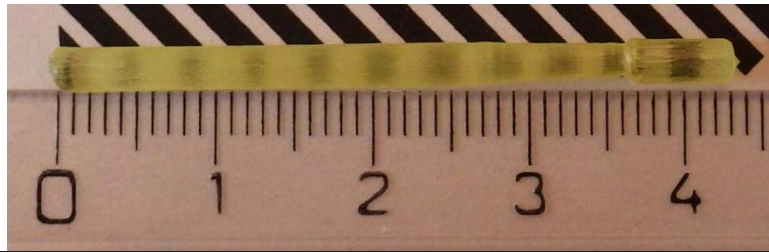
LuGAG:Ce 0.2% Mg 300 ppm



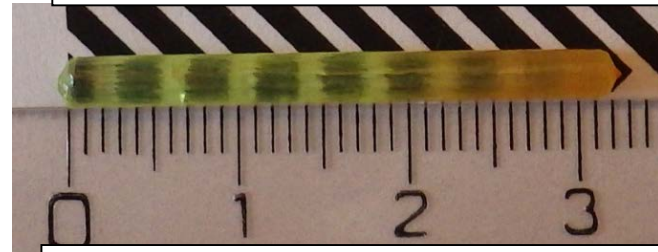
LuGAG:Ce 0.2% Mg 900 ppm



LuGAG:Ce 0.2% Mg 3000 ppm



Lu_{2.97}Ga₃Al_{2.03}O₁₂:Ce 0.2% Mg 300 ppm



Lu_{2.91}Ga₃Al_{2.09}O₁₂:Ce 0.2% Mg 300 ppm

Atmosphere: Ar+O₂, flow 0.5l/min, **Pulling speed:** 0.07-1 mm/min, Ir crucible, LuAG <100> seed
O₂ introduced to suppress Ga evaporation

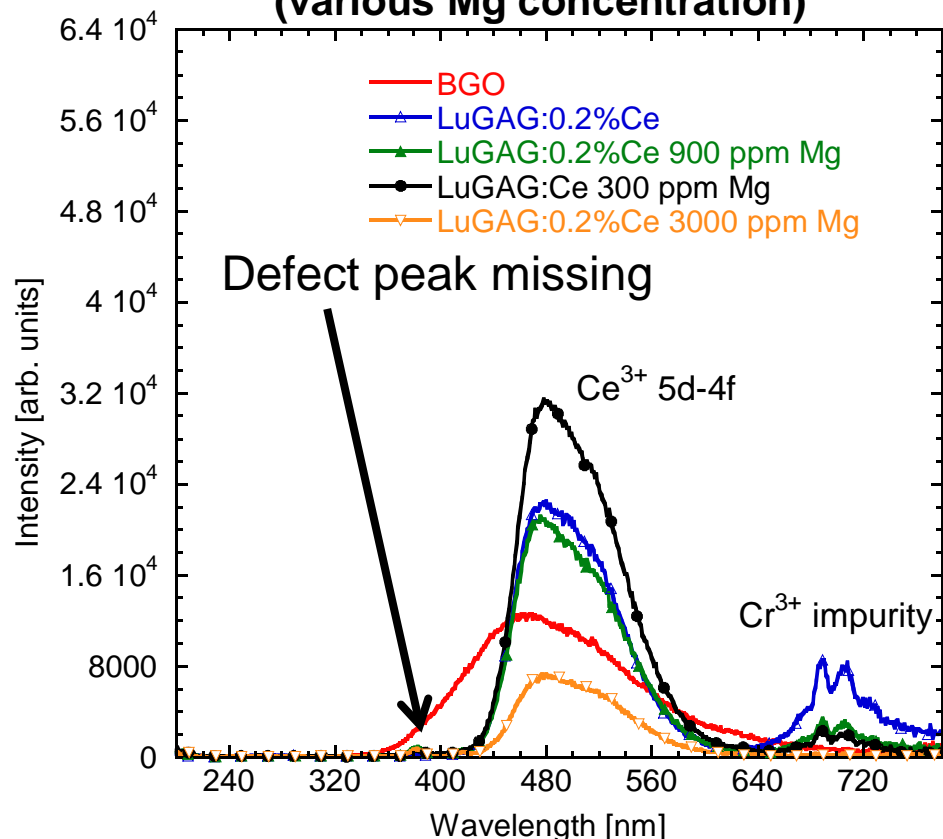
Excess of Ga₂O₃ added to the starting powder mixture to compensate for the Ga evaporation

XRD showed 2-3 different garnet phases of very close compositions.

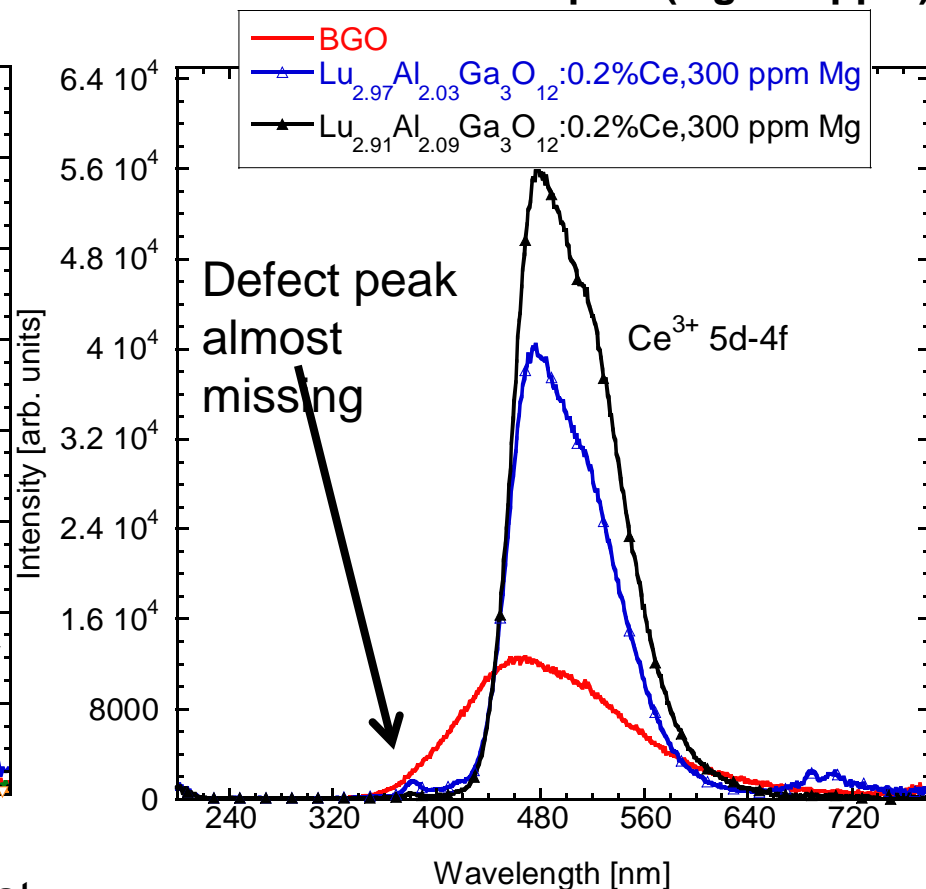
No annealing performed yet

Radioluminescence(RL) of LuGAG:Ce, Mg (X-ray excitation)

**Stoichiometric samples
(various Mg concentration)**



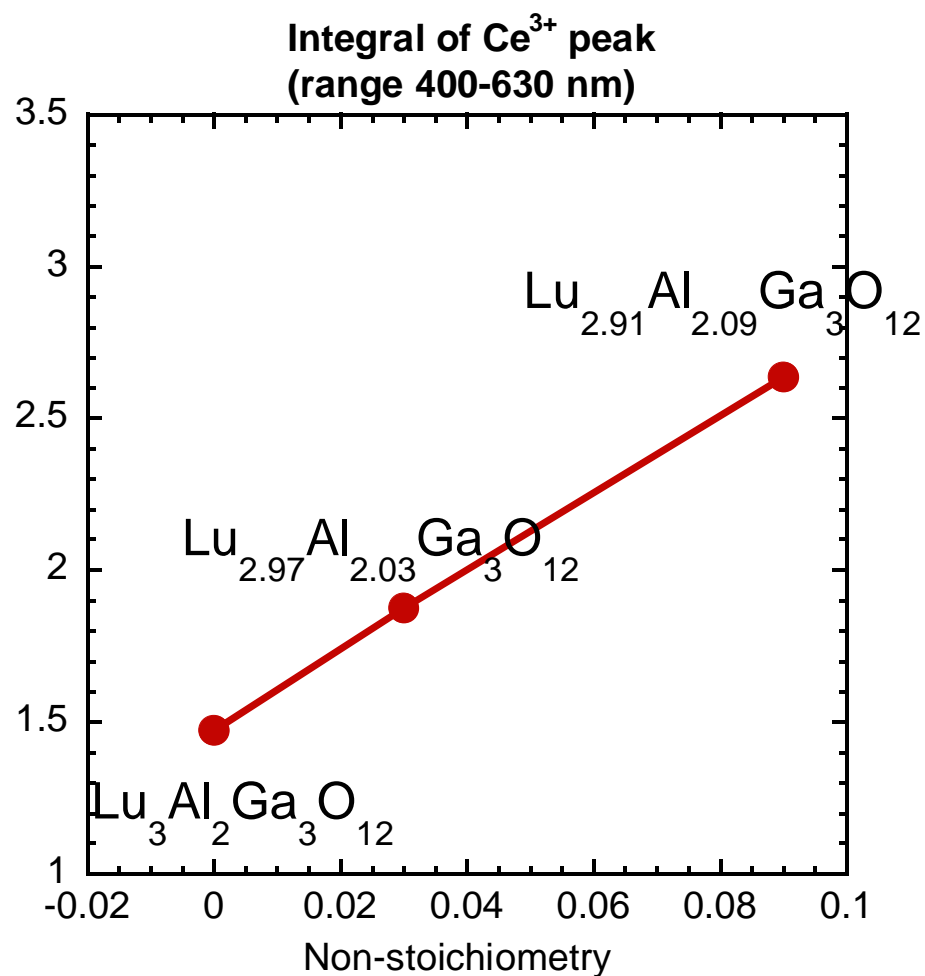
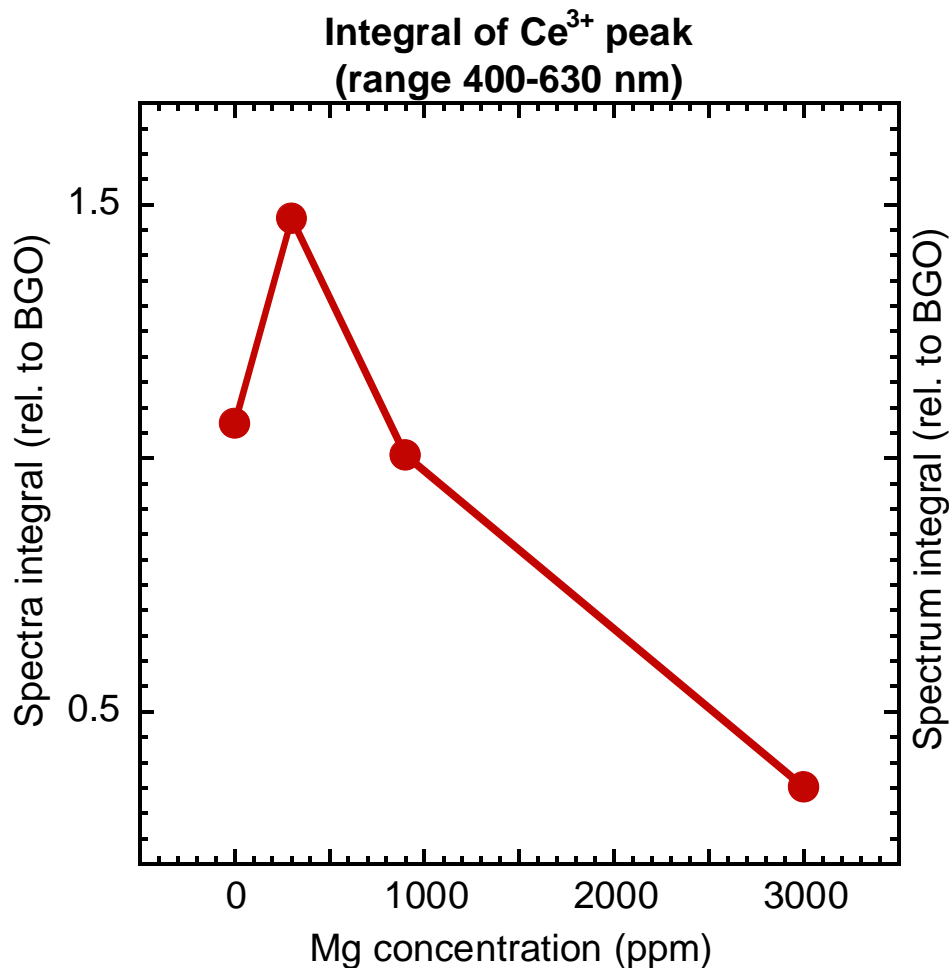
Non-stoichiometric samples (Mg 300 ppm)



For the **stoichiometric** samples, the highest intensity is for the Mg 300 ppm. **Higher Mg concentration leads to intensity decrease** – unlike for the Ga-free counterparts
Defect peak completely suppressed!
Shift of the emission to shorter wavelength!

Non-stoichiometry again significantly increases the radioluminescence intensity when compared to the stoichiometric samples.
 Negligible defect emission observed – caused by the non-stoichiometry?

Radioluminescence of LuGAG:Ce, Mg (general trends)



Stoichiometric samples:

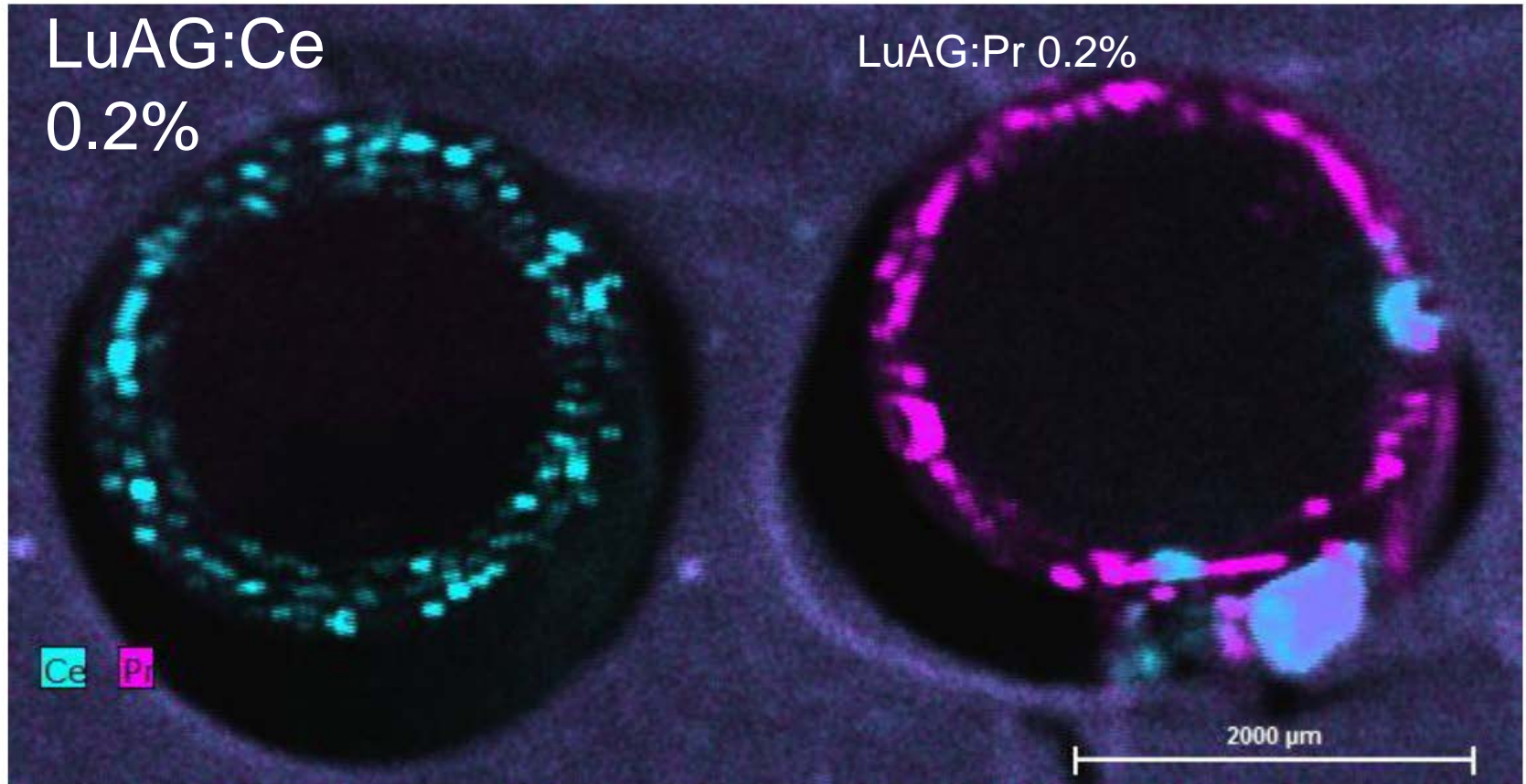
300 ppm Mg – positive effect

Increased Mg concentration leads to decrease of radioluminescence intensity

Non-stoichiometric samples (Mg 300 ppm):

Increased non-stoichiometry leads to significant increase of radioluminescence intensity

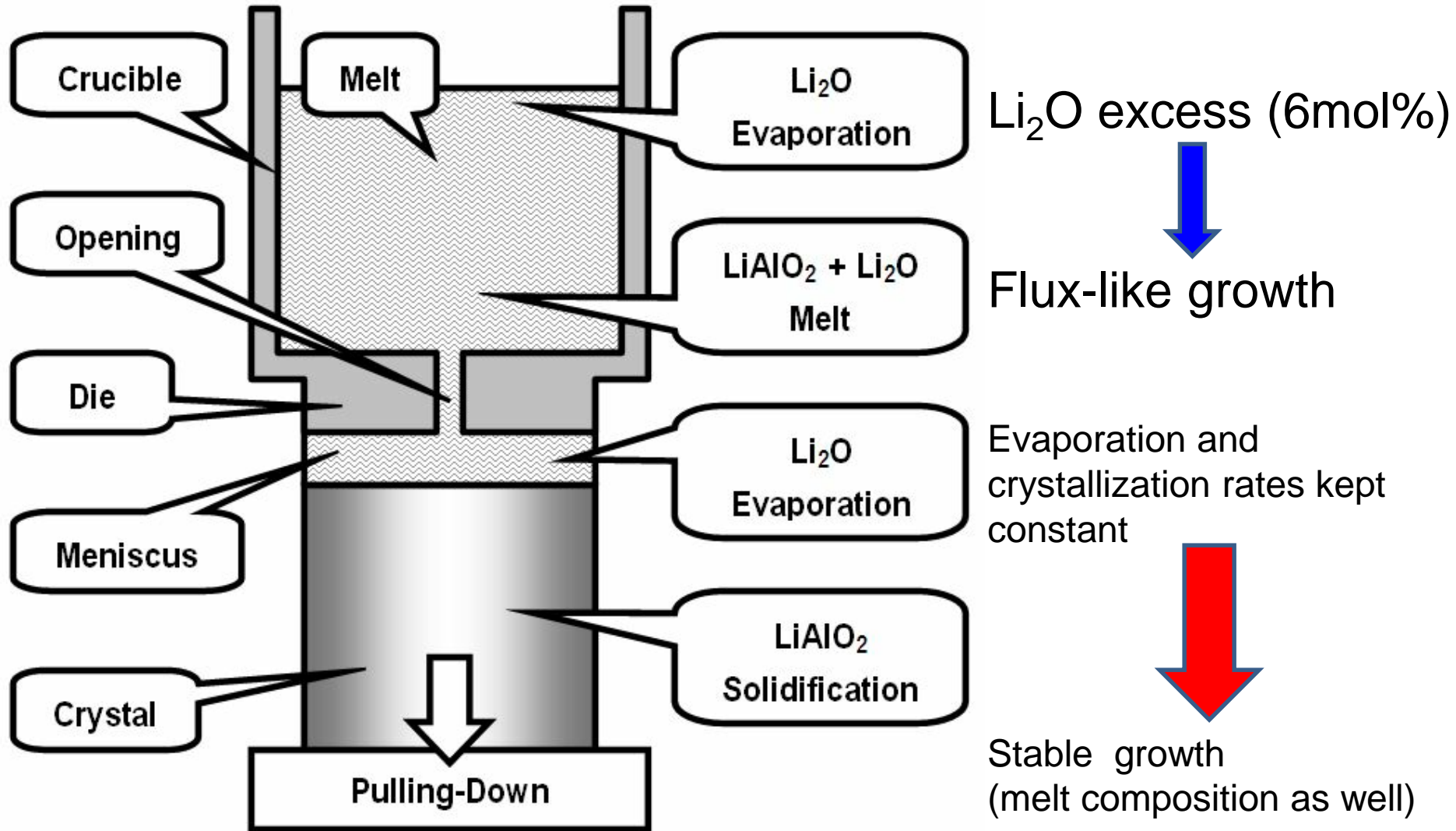
μ XRF (micro X-ray fluorescence)



Segregation of Ce (Pr) dopants – rejected to the surface
Similar was observed for LuGAG

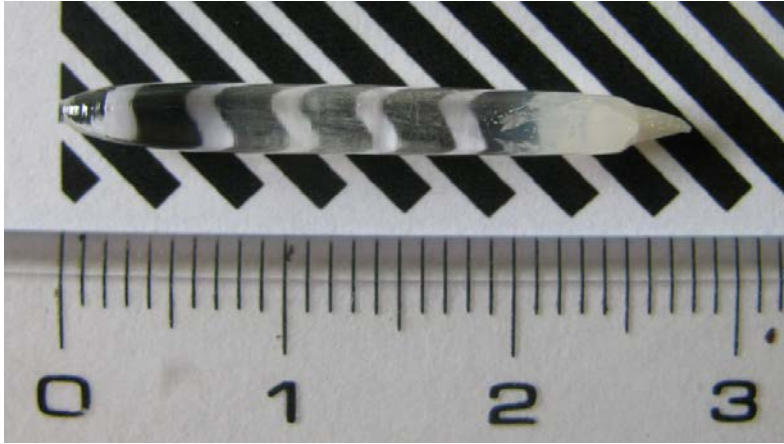
Micro-pulling-down method
Li-containing oxide crystals

Processes in the crystal growth of LiAlO_2

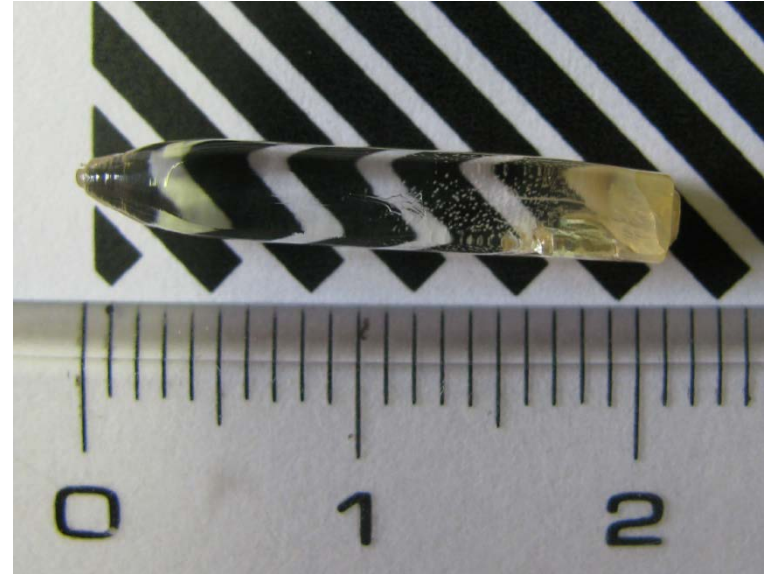


$$\text{LiAlO}_2(\text{melt})/\text{Li}_2\text{O}(\text{melt}) = \text{LiAlO}_2(\text{crystal})/\text{Li}_2\text{O}(\text{evaporation}) = \text{constant}$$

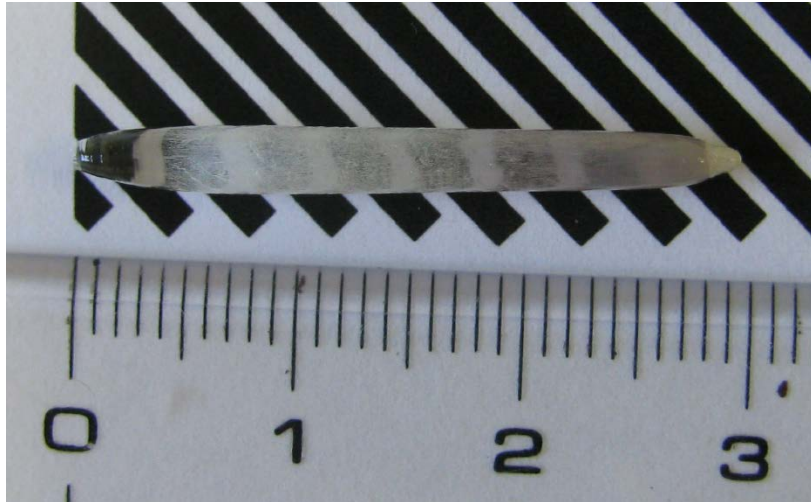
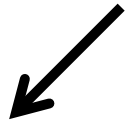
LiAlO₂ grown crystals



LiAlO₂:Ti0.1%,Mg0.1%



LiAlO₂:Fe0.1%
Shaped crystal

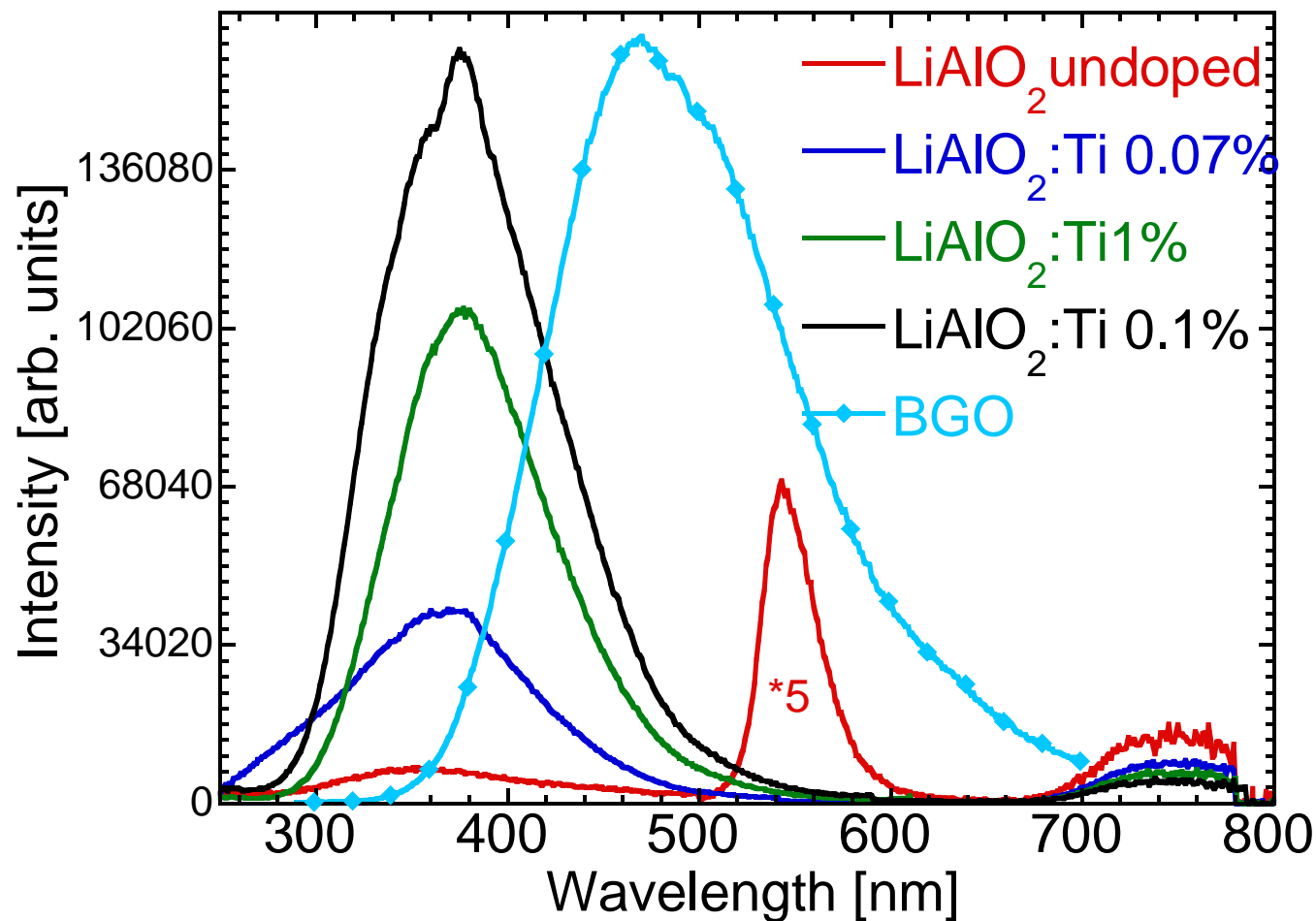


LiAlO₂:Ti0.1%

XRD analysis confirmed the LiAlO₂ tetragonal γ -phase

LiAl₅O₈ or Li₅AlO₄ phases confirmed at the very end of some crystals

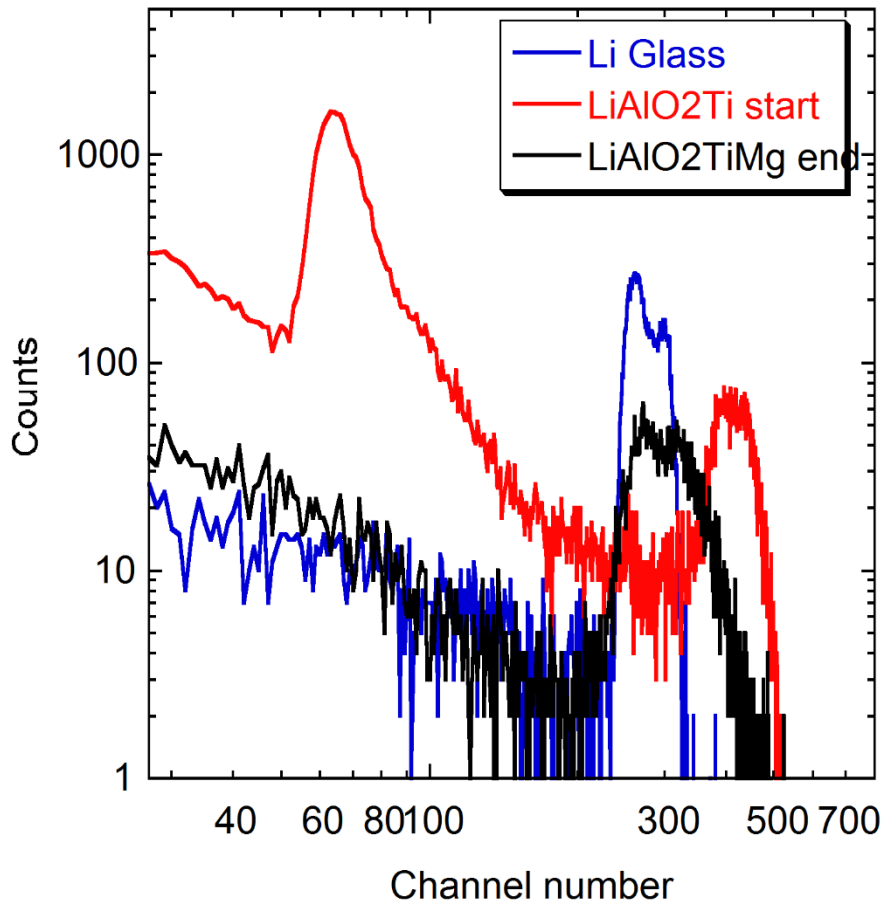
Radioluminescence measurements



Spectra comparable in absolute scale, overall scintillation efficiency of LiAlO₂:Ti 0.1% is **100%BGO!!**

Undoped sample – host related emission (present also in the Ti-doped sample)

Neutron response (^{252}Cf)

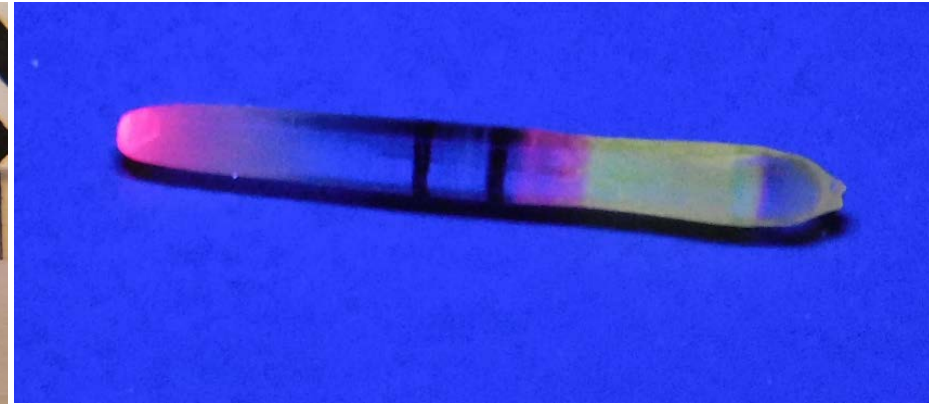
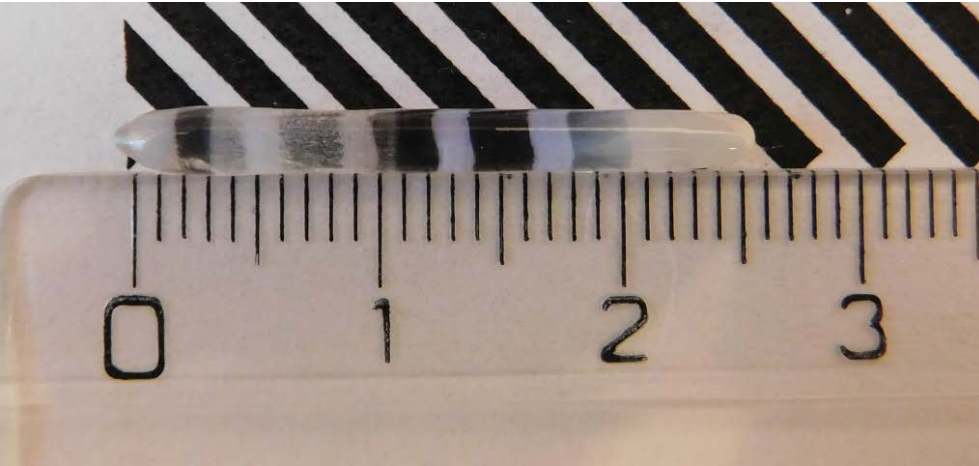


^{252}Cf neutron source used

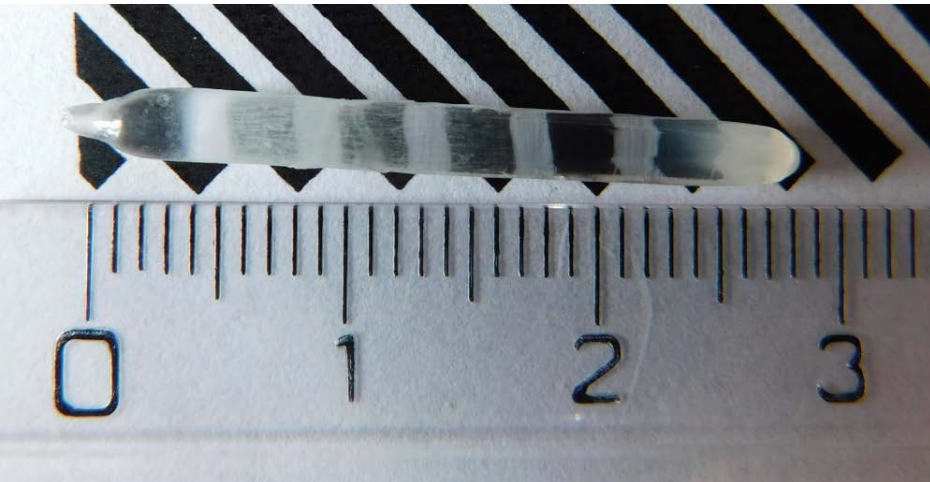
Data corrected for shaping amplifier gain and photomultiplier spectral sensitivity
Shaping time 10 μs

The neutron light yield exceeds that of GS20 Li-glass!
(6000 photons/neutron)

LiAlO₂- Grown crystals



LiAlO₂:Si0.1%



LiAlO₂:Sn1%

Atmosphere: Ar, flow 0.5l/min, **Pulling speed:** 0.07-1 mm/min, Ir crucible, Ir seed

0.5g of starting material, 0.06g of Li₂CO₃ excess to compensate for Li evaporation

XRD showed tetragonal high-temperature γ -modification

LiAl₅O₈ Li-poor phase detected at the end of crystal

Crystal growth of Li_4SiO_4 by micro-pulling-down method

Flux-like growth

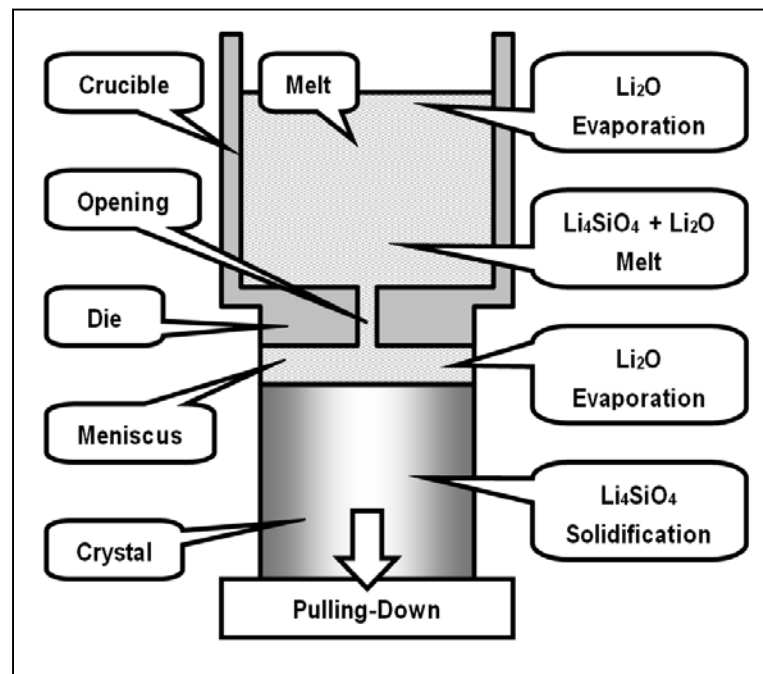
Atmosphere: Ar

Pulling speed: 0.05-0.07 mm/min,

Seed: "spiked" Ir wire

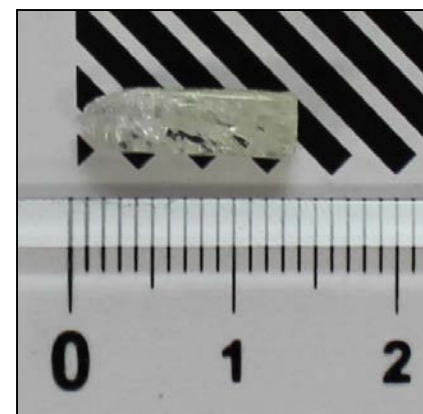
Ir crucible with a die (square or round shape)

Li_2CO_3 excess (5 mol%) added to improve melt properties (wettability) and **compensate for Li evaporation**



$$\begin{aligned} \text{Li}_4\text{SiO}_4(\text{melt})/\text{Li}_2\text{O}(\text{melt}) &= \\ \text{Li}_4\text{SiO}_4(\text{crystal})/\text{Li}_2\text{O}(\text{evaporation}) &= \\ &= \text{constant} \end{aligned}$$

Grown crystal
Many cracks observed



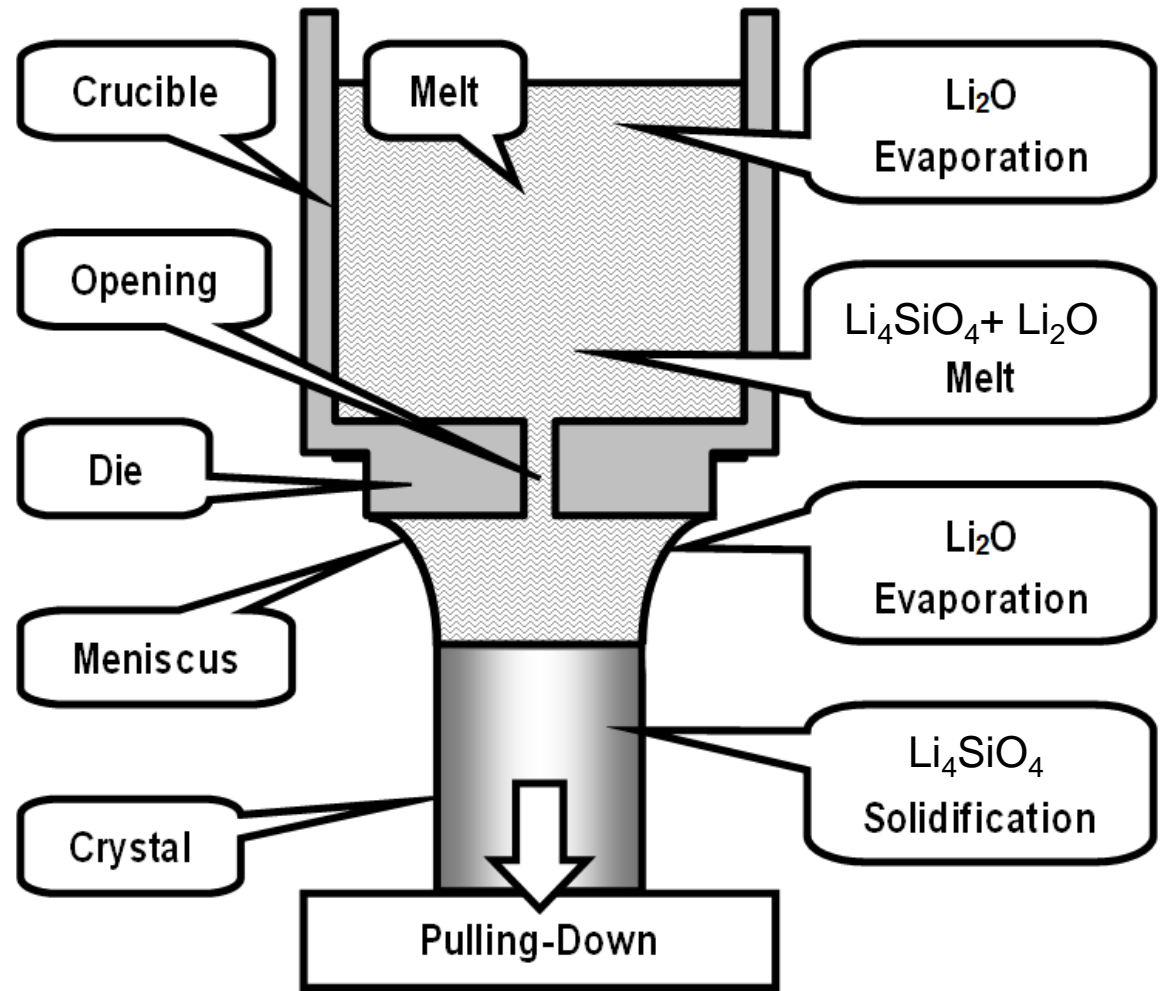
Crystal growth of Li_4SiO_4 by micro-pulling-down method

Optimization of crystal growth conditions:

Increase of the heating power led to increase of meniscus thickness and decrease of crystal diameter.

Increase of mixing and mass exchange at the melt-solid interface

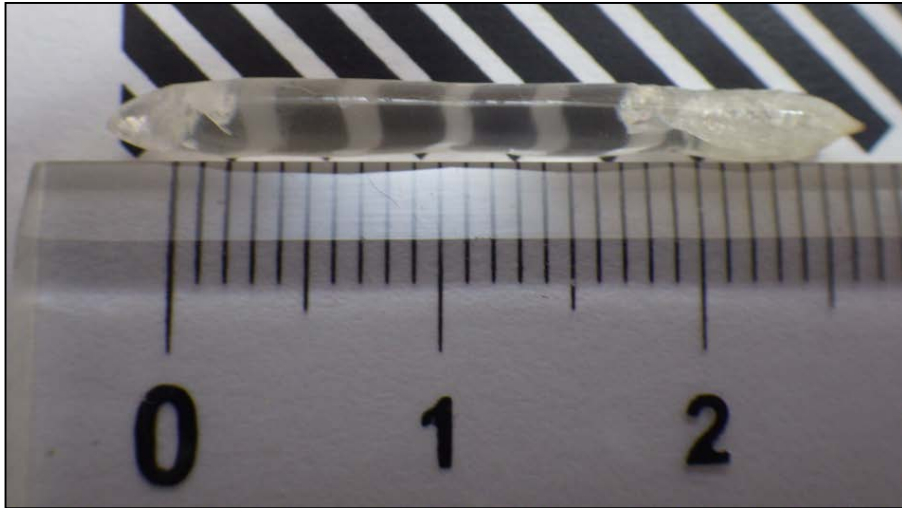
Both the radial and vertical gradient became more shallow and growth of good quality crystals was enabled.



Mass balance of the flux-like crystal growth:

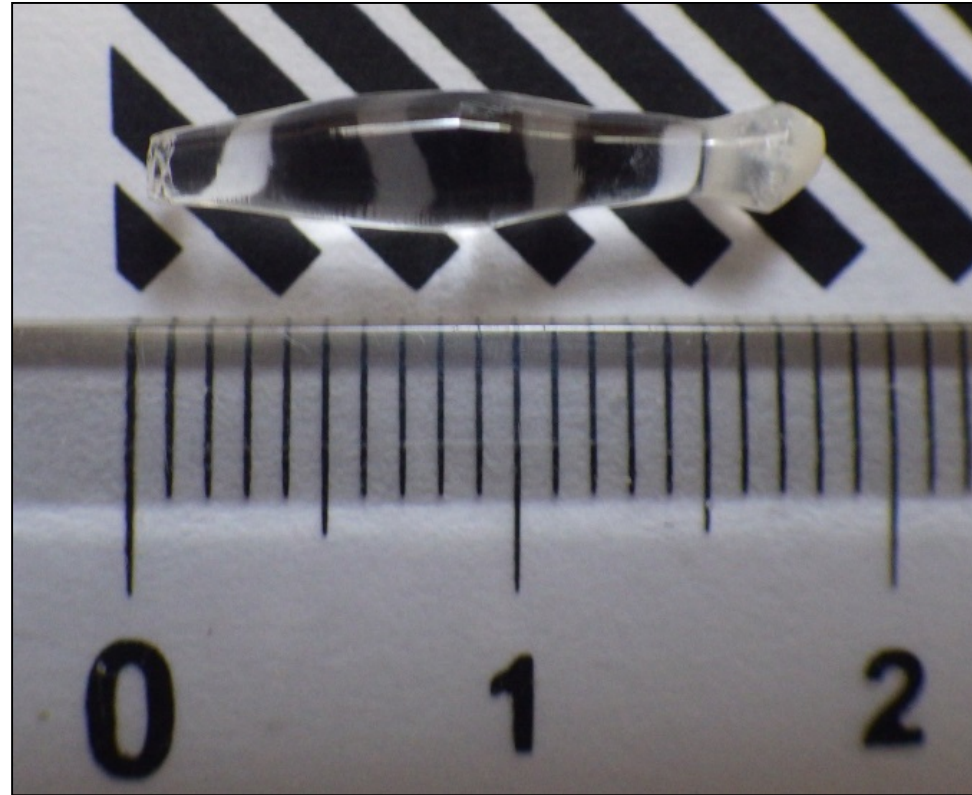
$$\text{Li}_4\text{SiO}_4(\text{melt})/\text{Li}_2\text{O}(\text{melt}) = \text{Li}_4\text{SiO}_4(\text{crystal})/\text{Li}_2\text{O}(\text{evaporation}) = \text{constant}$$

Li_4SiO_4 - grown crystals



Li_4SiO_4 undoped

Reaction with Ir crucible – slightly
cracky, brownish color

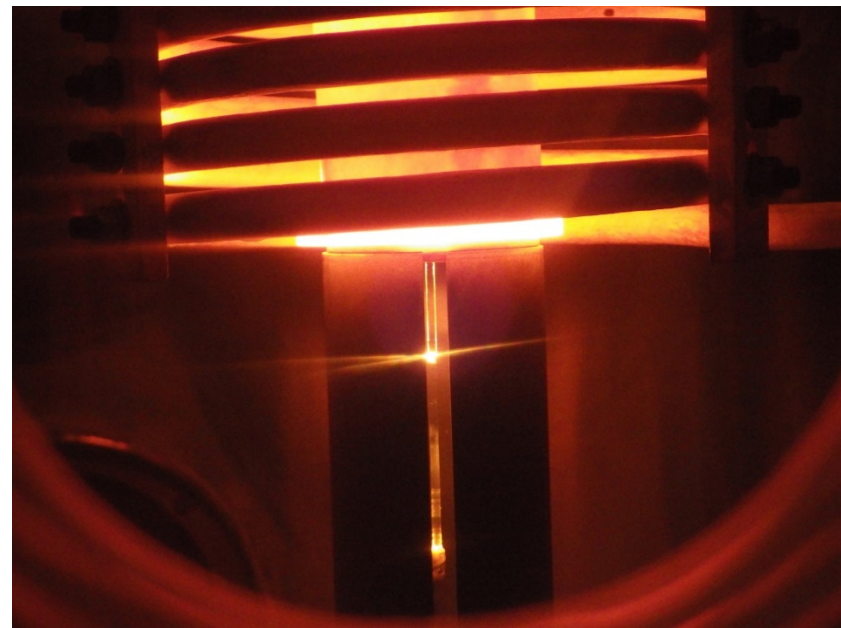
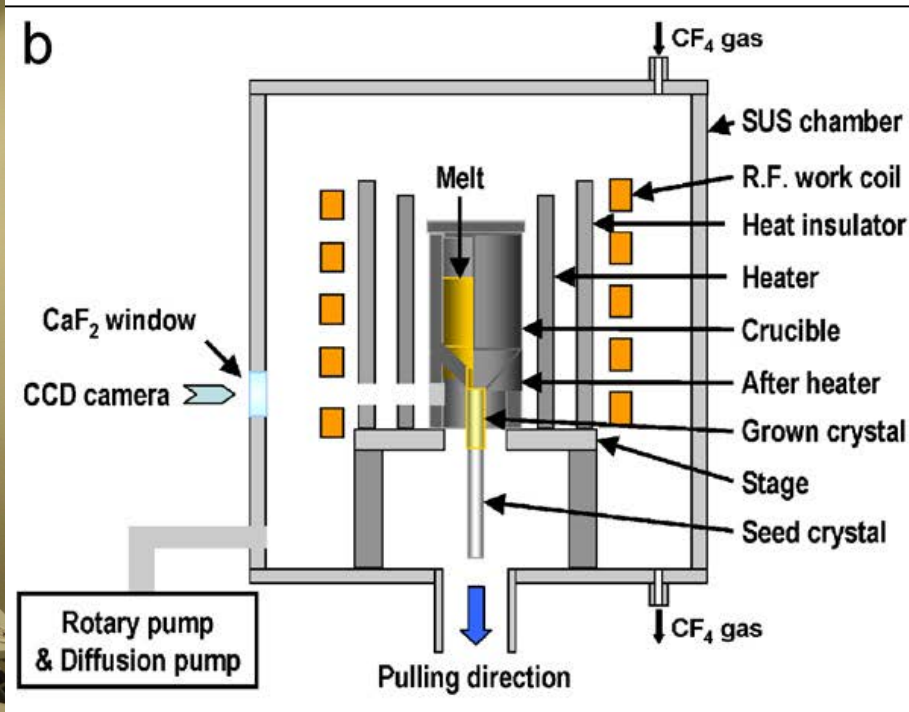


Li_4SiO_4 :Ti 0.2%

XRD confirmed Li_4SiO_4 monoclinic phase (PDF#37-1472)

Micro-pulling-down method Fluoride crystals

Fluoride crystal growth



Growth conditions

Bake out-procedure under high vacuum

Atmosphere:

$\text{Ar}+10\%\text{CF}_4$ (moisture scavenger!)

Carbon crucible: non-wetting melt

Crystal shape determined by the nozzle shape!

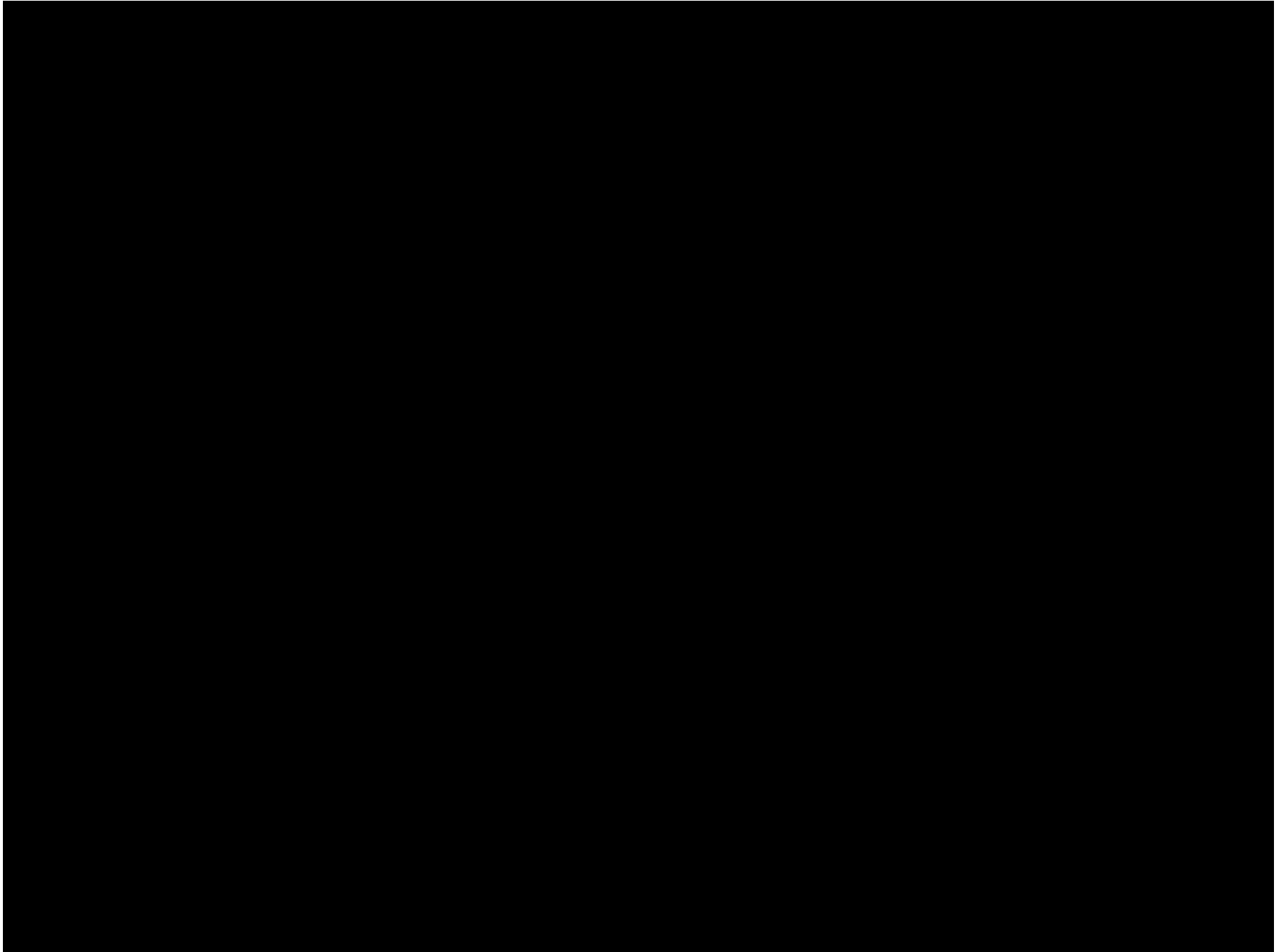
Direct contact of melt and the growing crystal
(not separated by a capillary)

Fluoride micro-pulling-down setup

Carbon crucibles

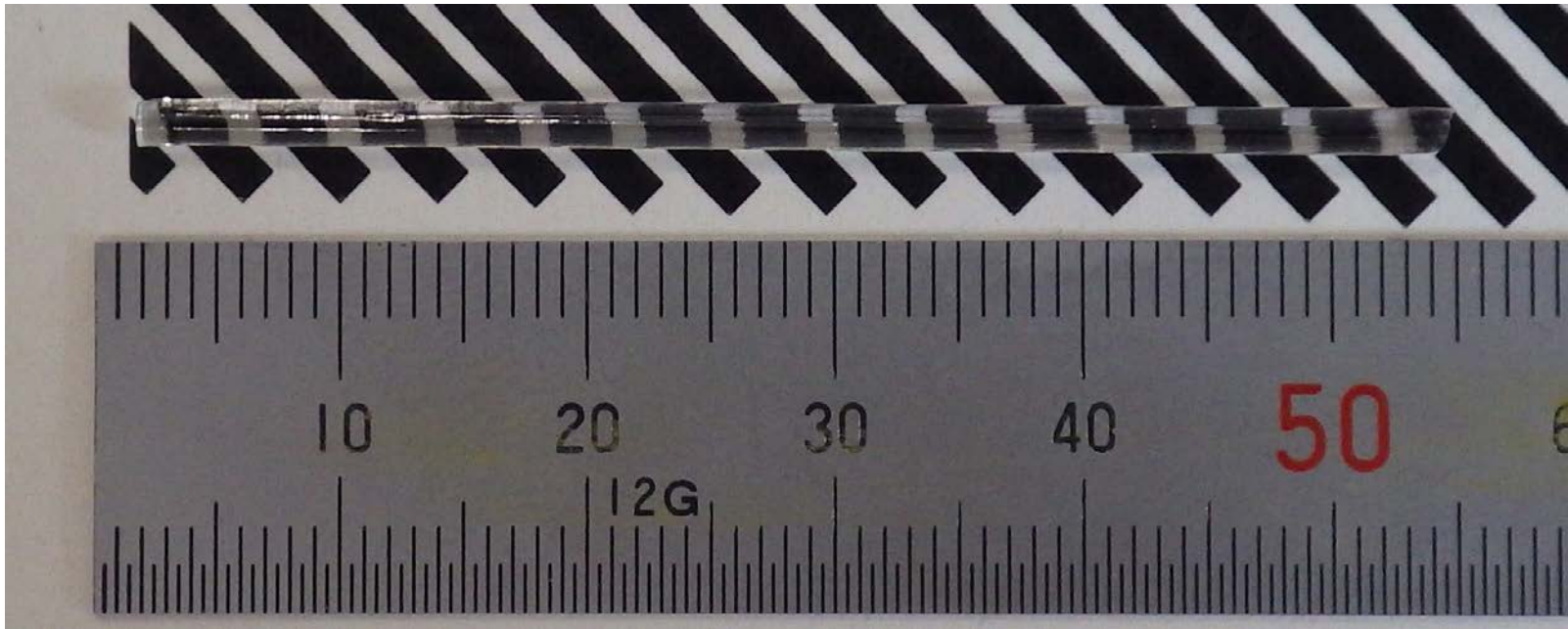


Micro-pulling-down method for fluorides



Fluoride micro-pulling-down setup

Grown crystal of CaF_2

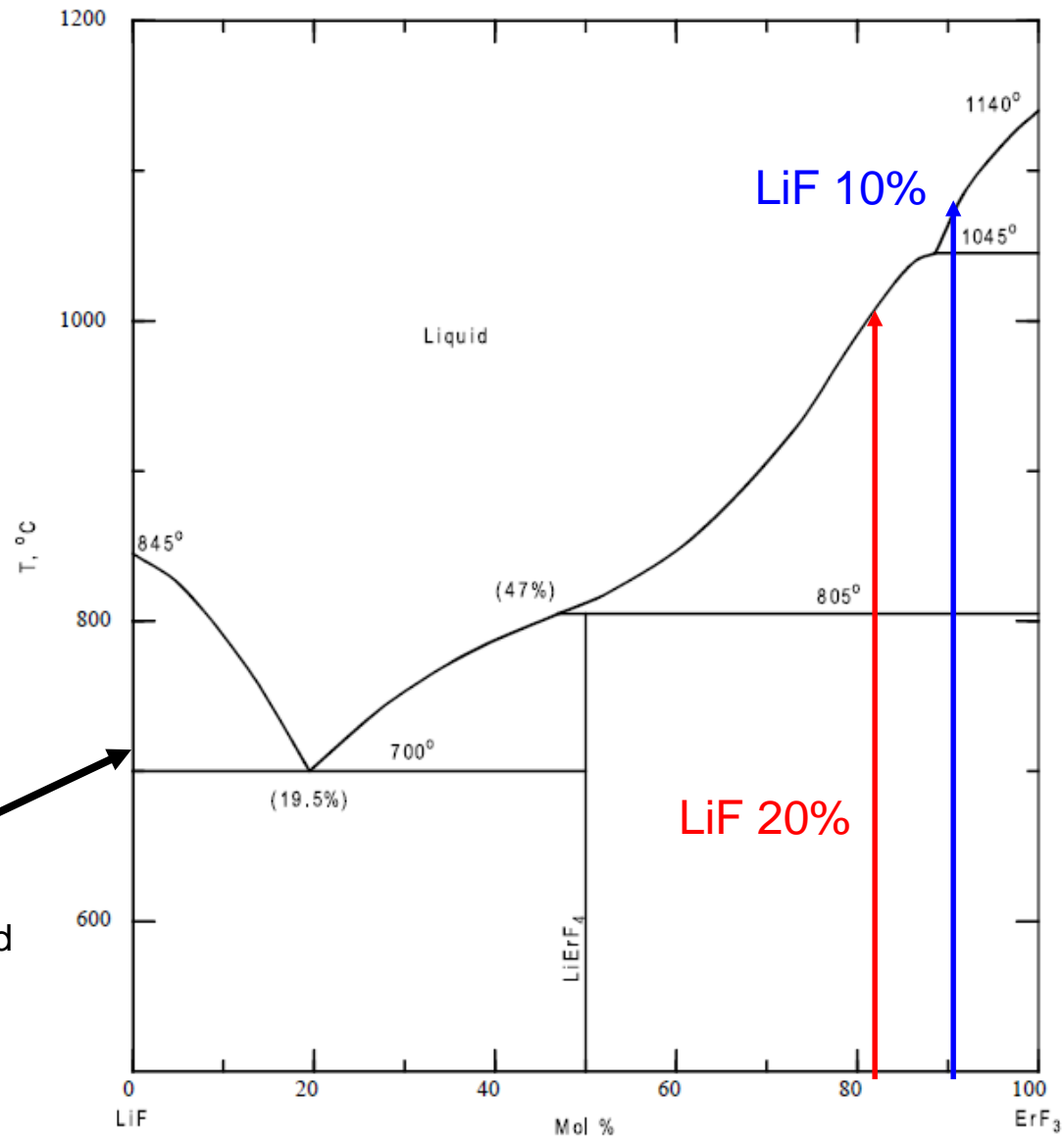


Nd-doped ErF₃

- Energy transfer from Er³⁺ to Nd³⁺?
VUV Analogue to PrF₃:Ce?
(A. Yoshikawa et al., J. Cryst. Growth 270, 427–432 (2004))
- high density (7.8 g/cm³) – high gamma ray or X-ray stopping power
- Challenging crystal growth – melting point 1140°C, phase transition (from hexagonal to orthorhombic) at ~1045°C

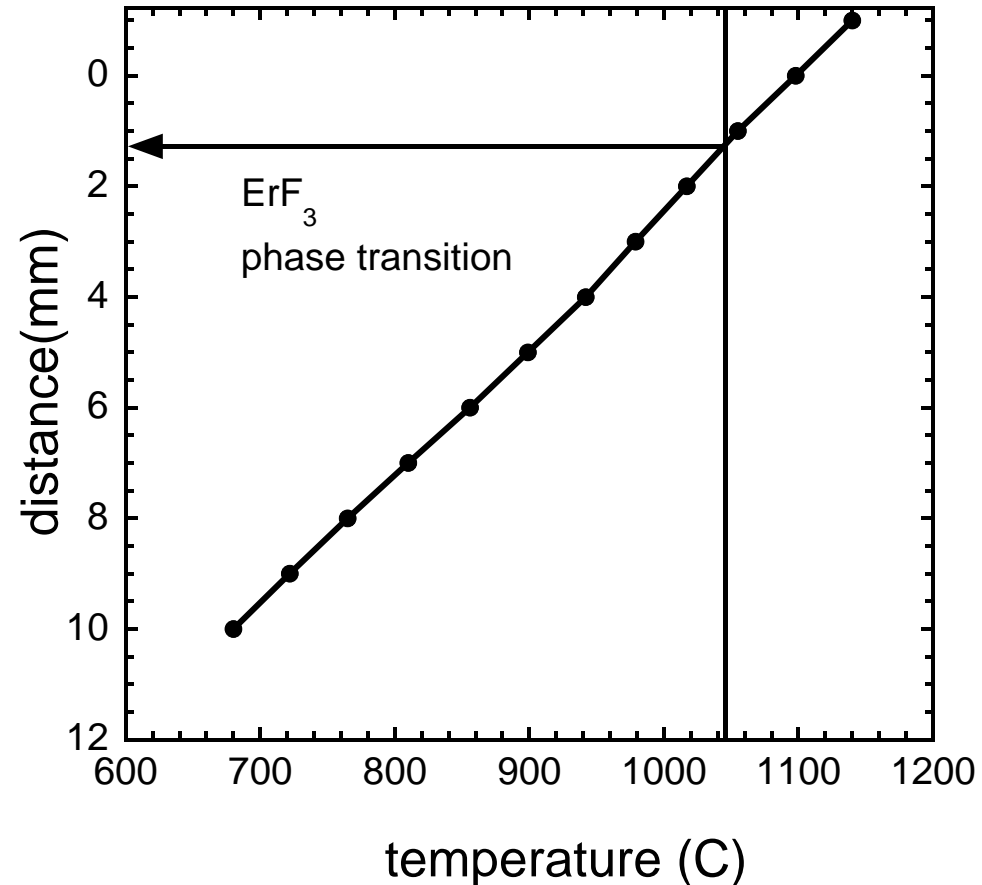
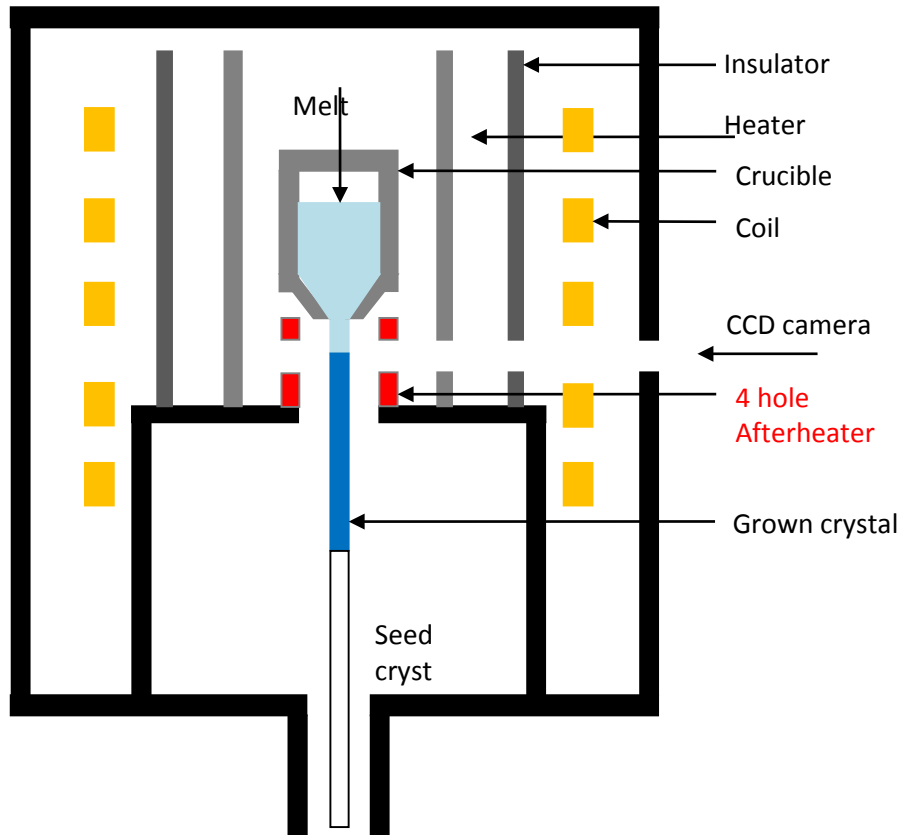
LiF-ErF₃ Phase diagram

According to I. A. Ivanova, M. A. Petrova, and I. G. Podkolzina, Zh. Neorg. Khim., 20 [8] 2292-2293 (1975); Russ. J. Inorg. Chem. (Engl. Transl.), 20 [8] 1273-1274 (1975).



LiF flux growth might be possible

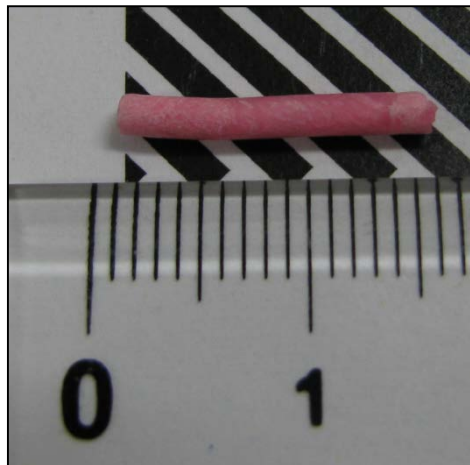
Crystal growth of tetragonal (low temperature) ErF_3 - LiF -flux



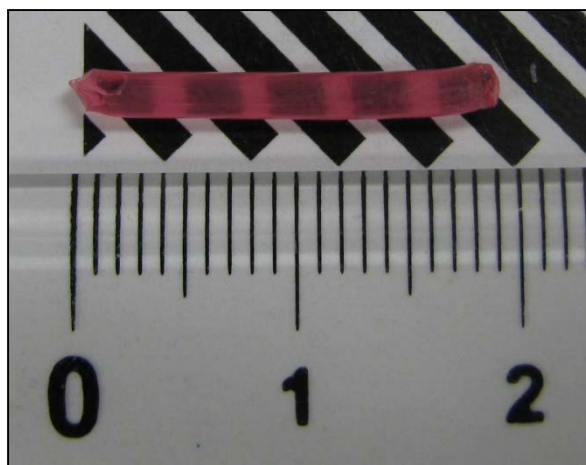
Ir-wire seed, LiF - flux introduced to diminish the melting point. **Steep gradient** at the crucible nozzle to facilitate melt supercooling

Standard hot zone, 4hole afterheater – makes the temperature gradient steeper

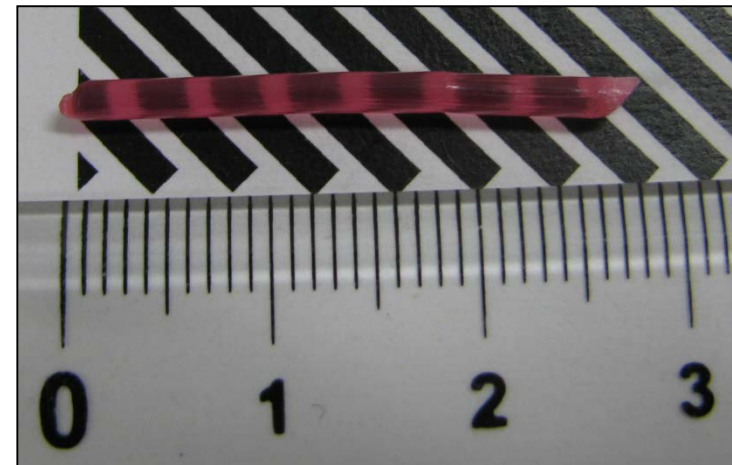
ErF₃, ErF₃:Nd – as grown crystals



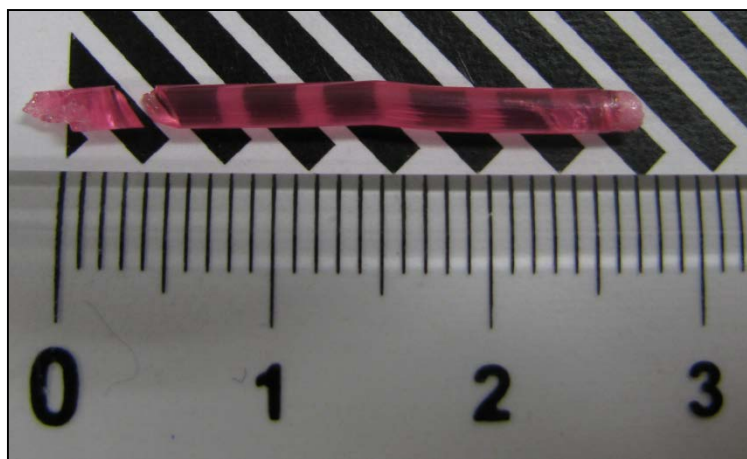
No LiF



LiF 20%



LiF 10%



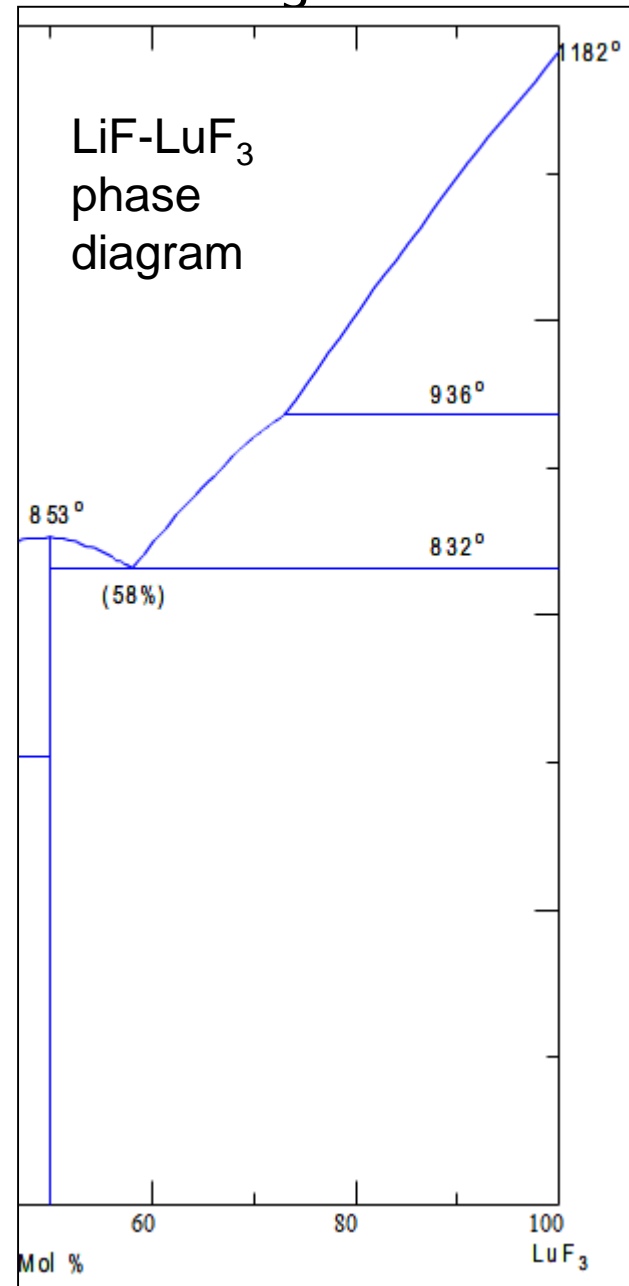
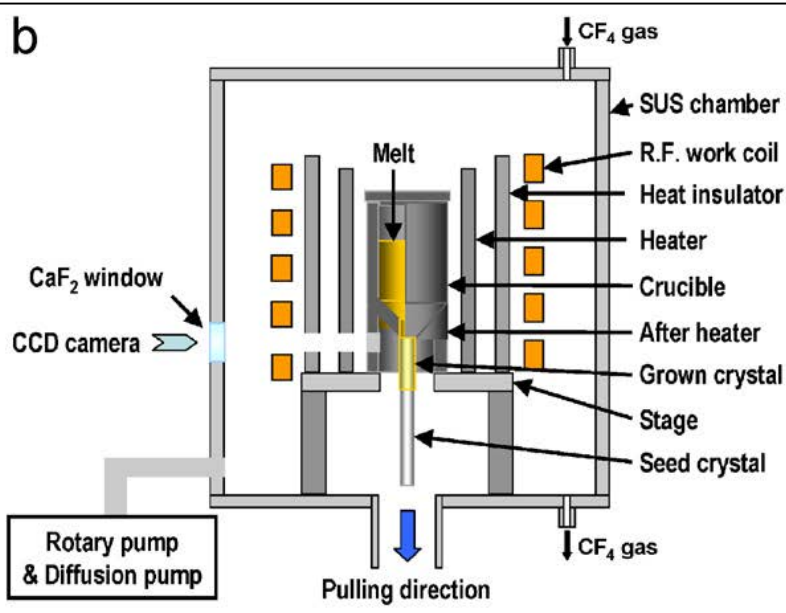
LiF 10%, Nd1% doping
Little cracks

XRD confirmed pure ErF₃ phase

LiErF₄ phase confirmed in crucible rest

For LiF 10% excess the composition corresponds to 90.9% ErF₃ and 9.1%LiF – still above the phase transition temperature (peritectic point around 12%LiF) – supercooling takes place

Micro-pulling-down method for LuF_3



Modification for fluorides:

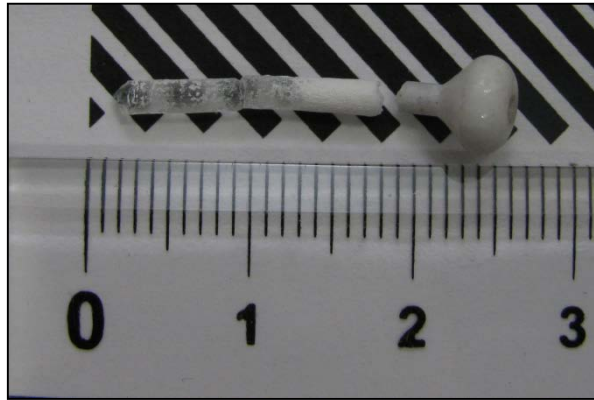
Graphite crucible, seed, evacuation and baking procedure,

Atmosphere: 90%Ar+10% CF_4 (moisture scavenger gas)

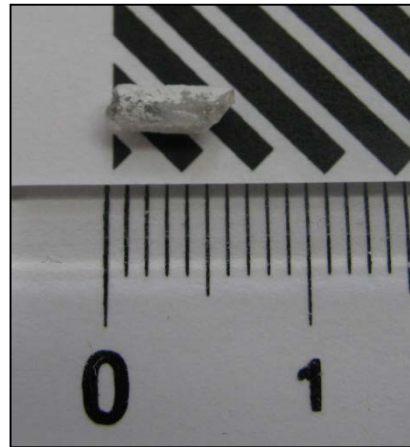
Crucible hole diameter: 2 mm

Pulling speed: 0.01mm/min. LiF flux to avoid phase transition (250°C below melting point 1182°), Self-cladding

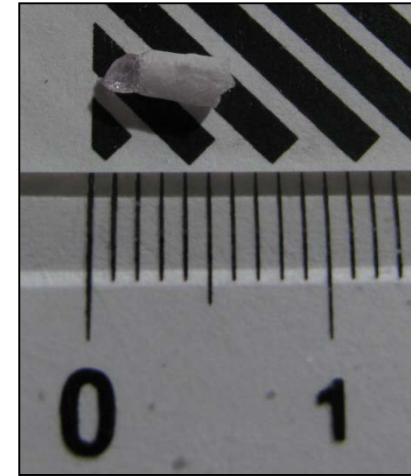
LuF₃-based VUV scintillators – examples of the as-grown crystals



LuF₃
undoped



LuF₃:Er1%



LuF₃:Nd1%



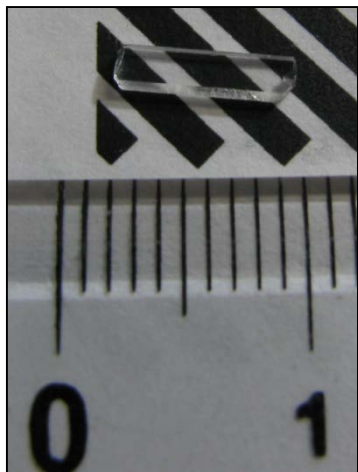
LuF₃:Er1%Nd1%

LiF flux, Ir-wire seed, pulling speed 0.01 mm/min, LuF₃ phase confirmed by XRD
Self-cladded with LiLuF₄

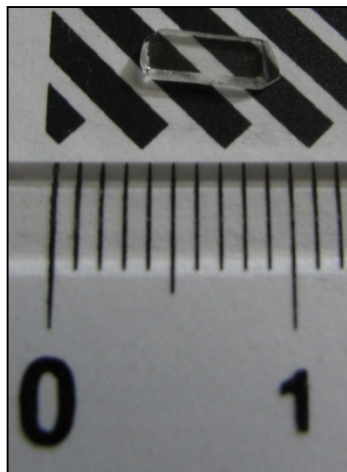
Er codoping – Improvement of energy transfer

Studied LuF_3 crystals

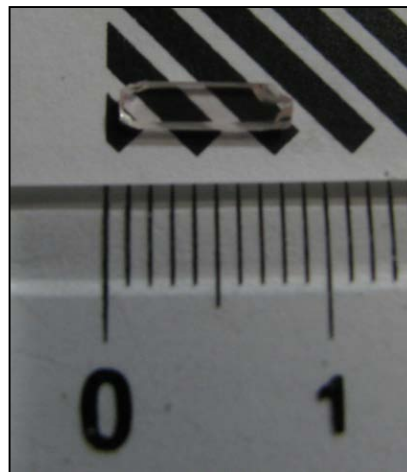
After cutting and polishing



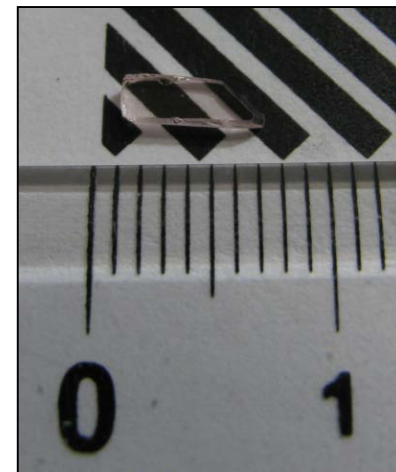
LuF_3
undoped



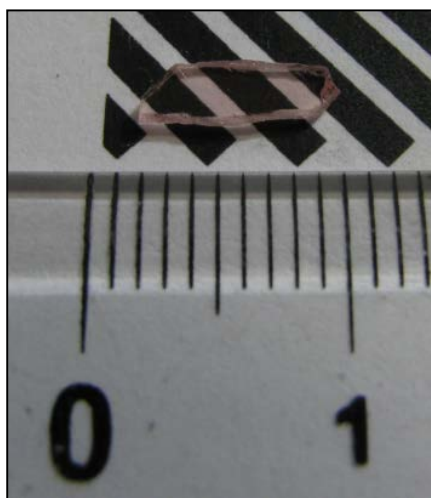
LuF_3 :Er1%



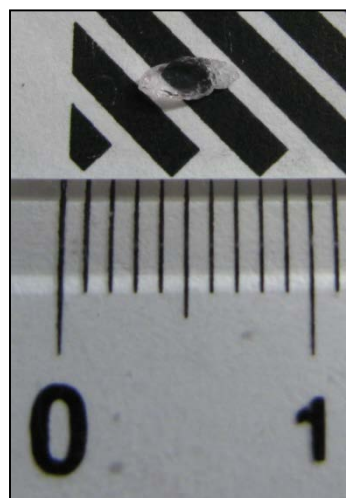
LuF_3 :Er3%



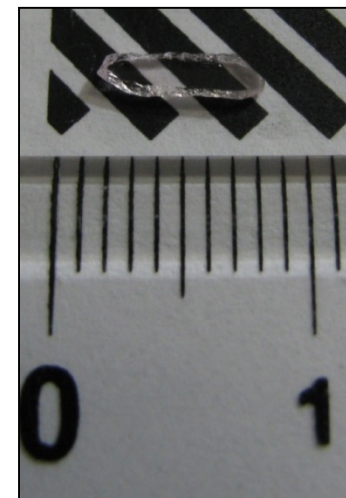
LuF_3 :Er5%



LuF_3 :Er10%

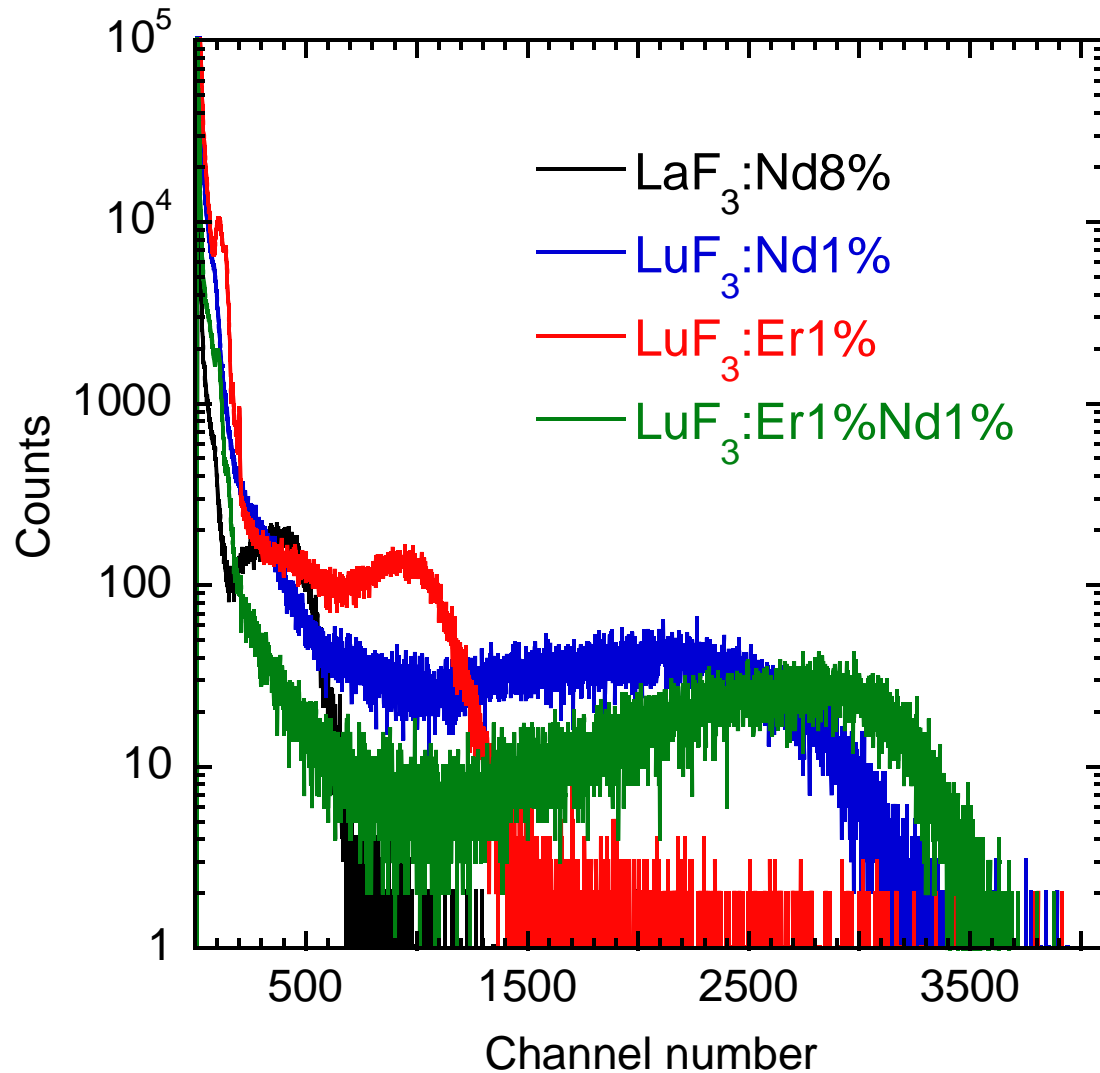


LuF_3 :Nd1%



LuF_3 :Er1%Nd1%

LuF₃ – Light yield – ²⁴¹Am alpha-ray excitation CsI photocathode photomultiplier



Channel numbers:

LaF₃:Nd8% : 250

LuF₃:Er1%: 970

LuF₃:Nd1%: 2350

LuF₃:Er1%Nd1%: 2847

Shaping time: 500ns

Slow HS component of Er³⁺ -
decay time of microsecond order
– lowered light yield for Er1%-
doped sample

Measurement of dependence of
the light yield on shaping time is
planned

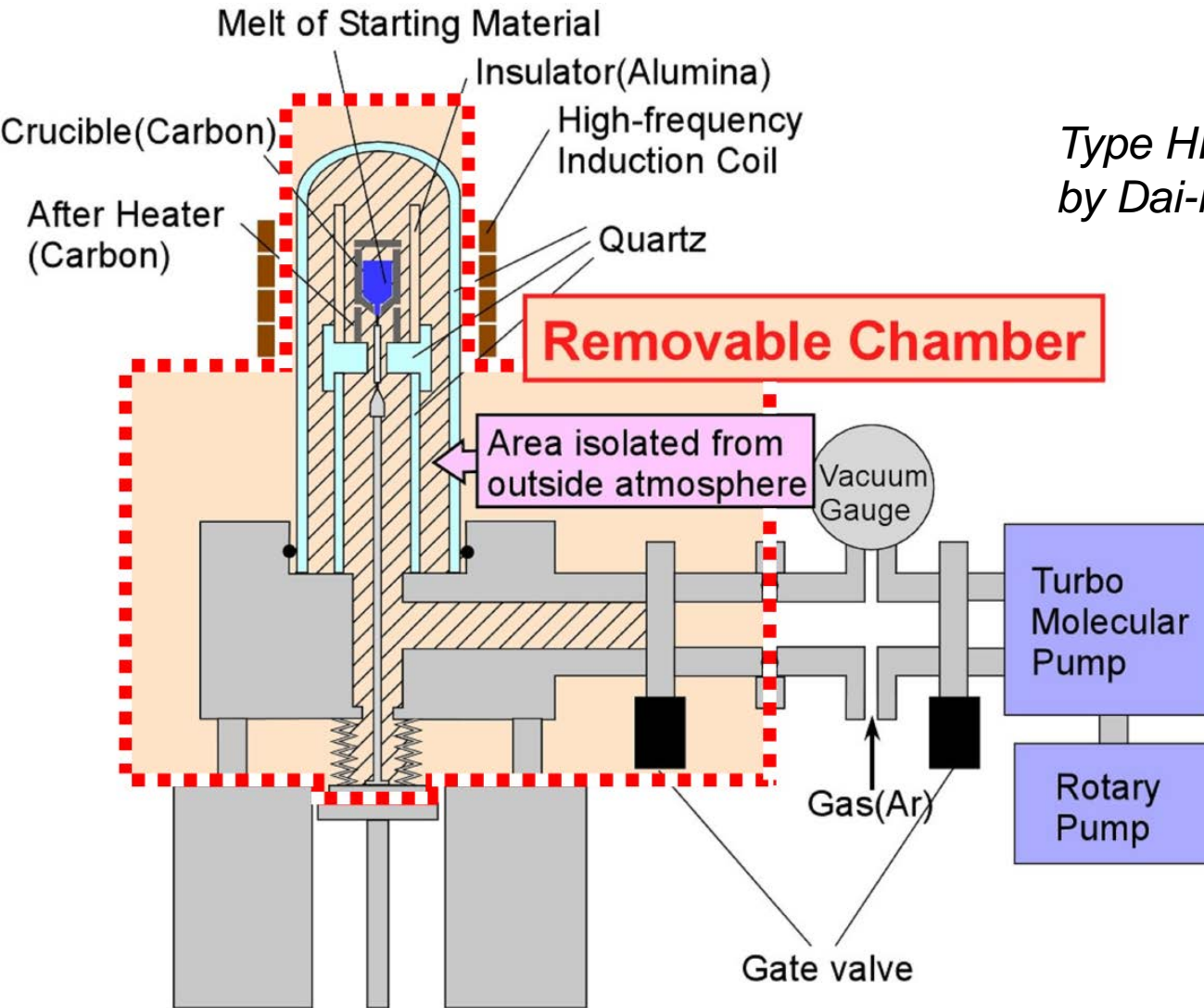
The Er,Nd doubly-doped sample
shows the highest light yield

Micro-pulling-down method

Halide crystals

Halide micro-pulling-down setup

*Institute of Physics, Czech
Academy of Sciences, Prague,
Installed in autumn 2017*



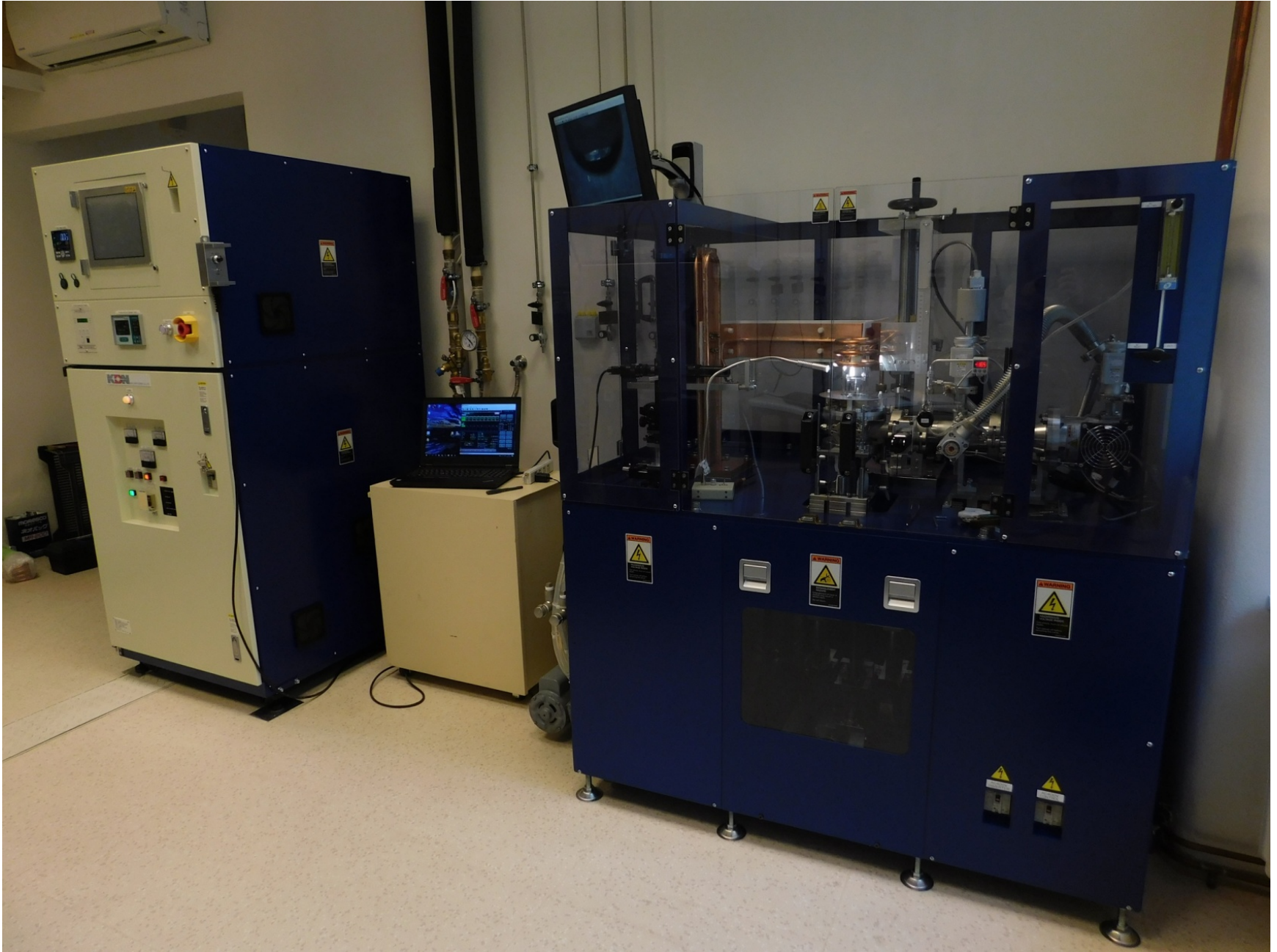
*Type HPI-01001
by Dai-ichi Kiden Co., Ltd. Japan*



Glove box

Halide micro-pulling-down setup

Type HPI-01001
by Dai-ichi Kiden Co., Ltd. Japan



Halide mPD - parameters



Operation panel (OP):

- Power output
- **Pulling rate (remote controller)**
- sequences (10 steps)
- max. distance setting
- **remote control by NB**

Specifications

RF Power Source	5 kW
Heat. temp.	1000 C (max.)
Removable chamber	YES
pulling rate [mm/min]	0.01-100 (step 0.01)
Coil (Cu)	3 turns (and 4 turns)
CCD Camera	Toshiba TELIBG202C
Crucible	Carbon

Notebook

- ✓ OP con.
- ✓ internet

Table

- ✓ Removable chamber
- ✓ CCD cam.
- ✓ **pulling mech.**
- ✓ VAC – RP, MP
- ✓ transformers

RF source

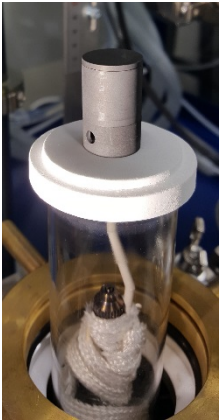
- ✓ OP control
- ✓ **manual** contr.

Halide micro-pulling-down setup

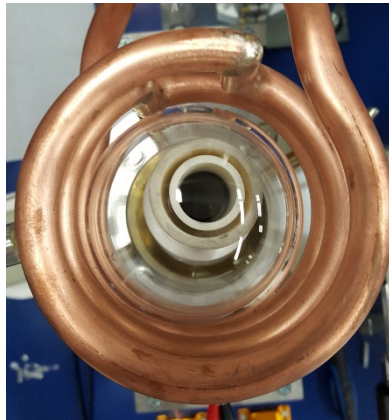
Carbon crucibles



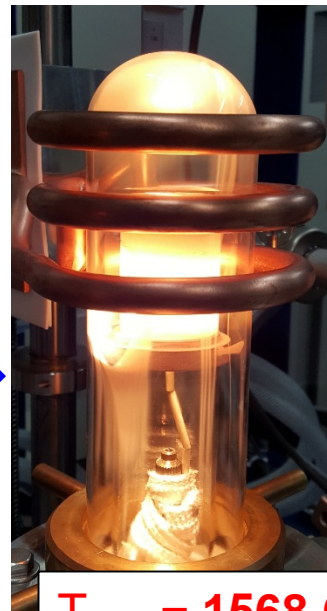
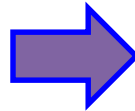
2nd Max. temp. meas.



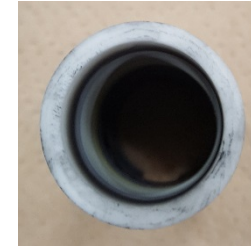
Al₂O₃ stage



double Al₂O₃ shield



High carbon evap.

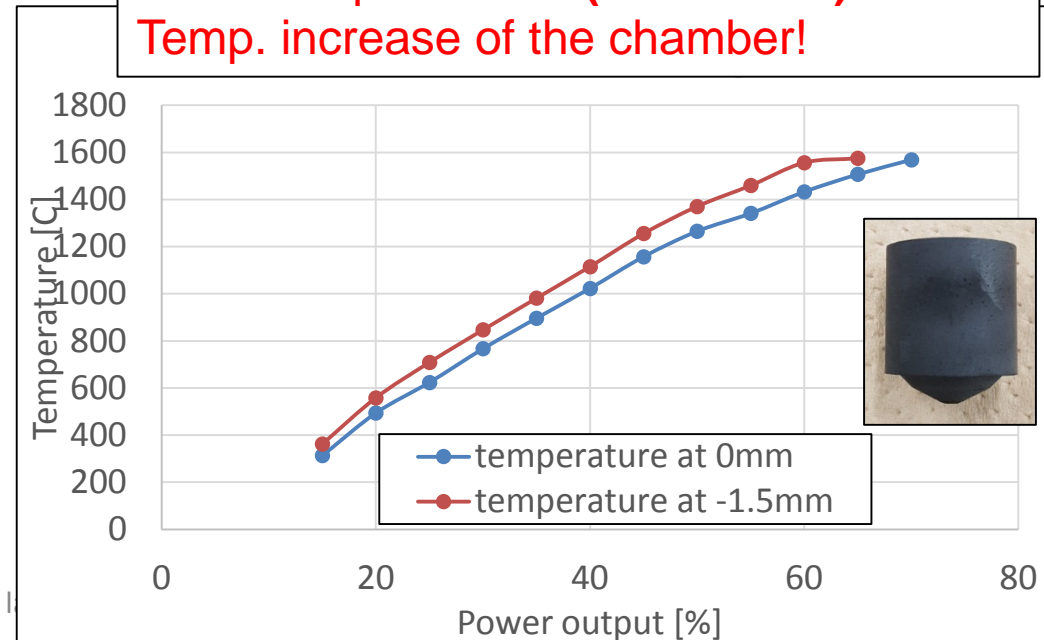


$T_{max} = 1568\text{ C (edge)}$

$T_{max} \sim 1650\text{-}1700\text{C (cruc.)}$

Power output = 70% (max. 5 kW)

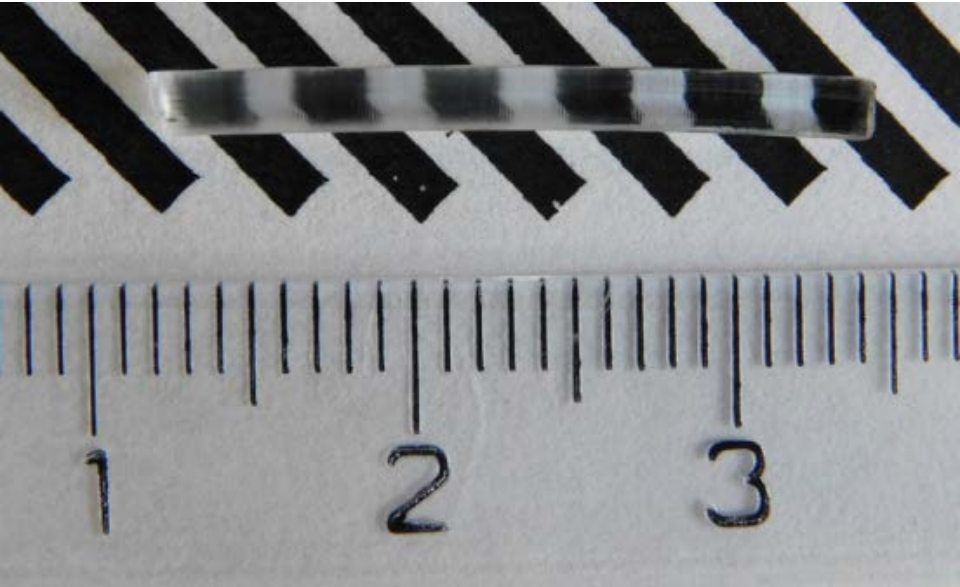
Temp. increase of the chamber!



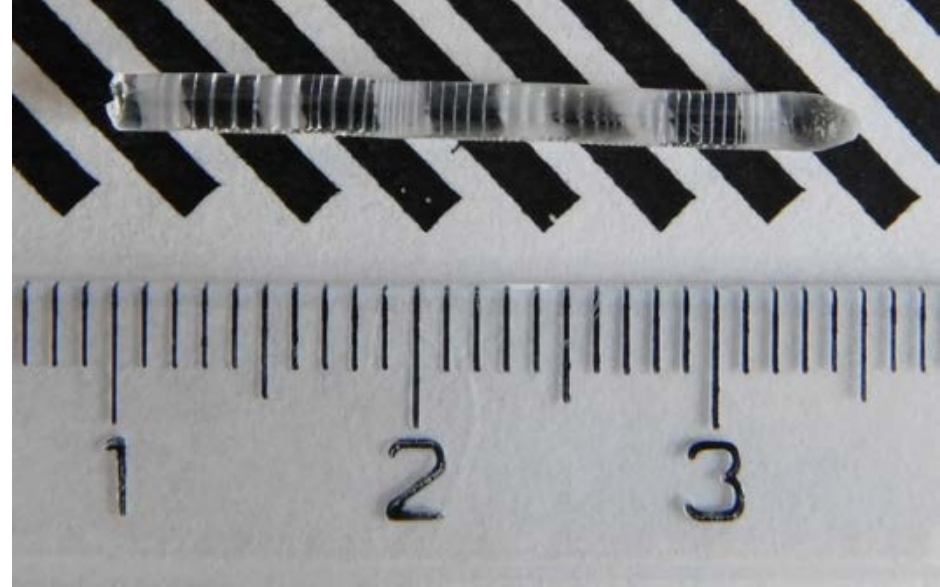
Conditions

crucible	carbon, hole 2mm (dia.)
afterheater	2x hole, 4 mm (dia.)
2x isolation	Al ₂ O ₃
Thermocouple	type B, Pt-Rh(6%)/Pt-Rh(30%)
stage	Al ₂ O ₃
atmosphere	Ar (6N)

Halide micro-pulling-down setup
– grown crystals
NaCl



0.1mm/min



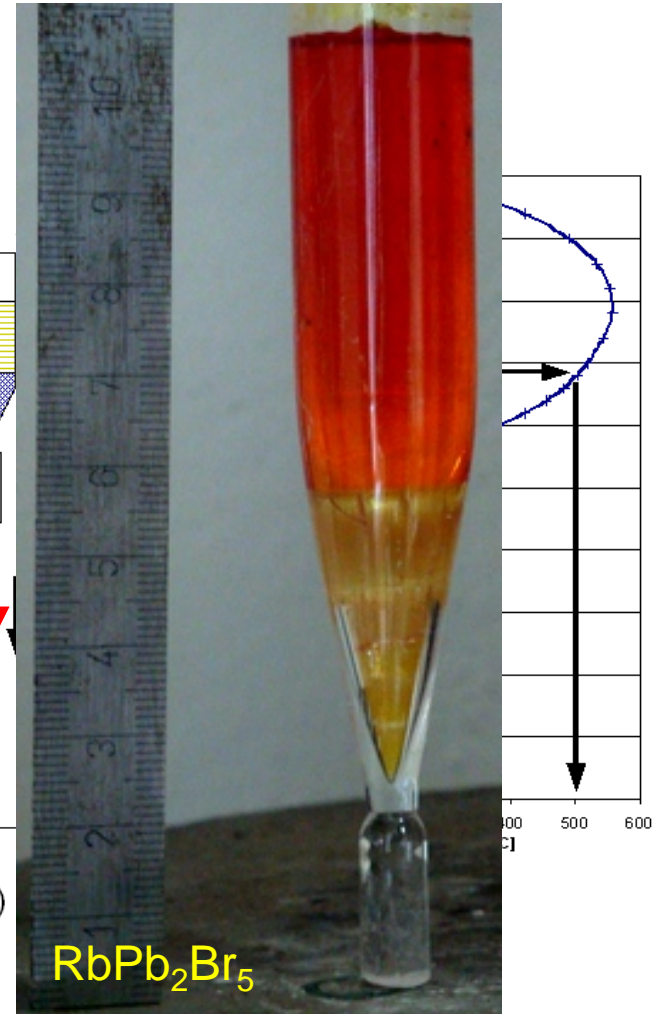
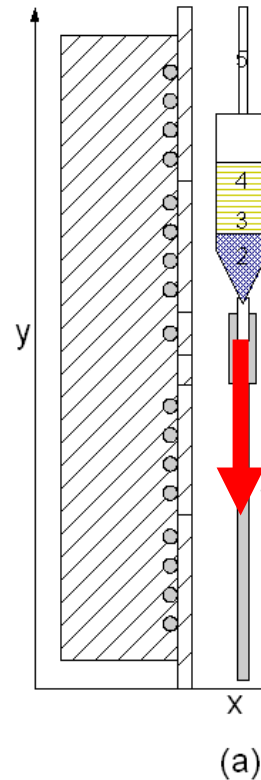
1mm/min

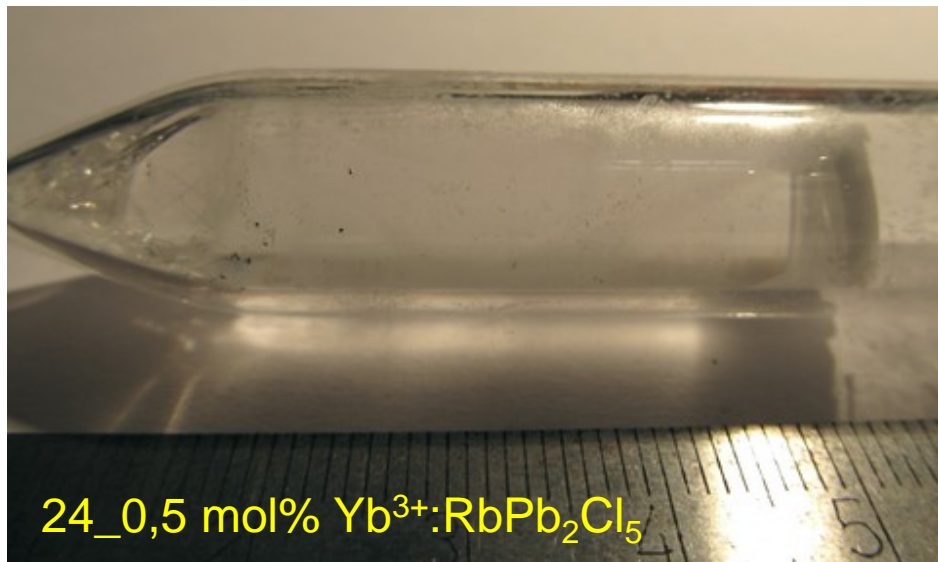
NaCl crystals grown by the new halide micro-pulling-down setup at a speed of 0.1mm/min (left) and 1mm/min (right)

Bridgman method

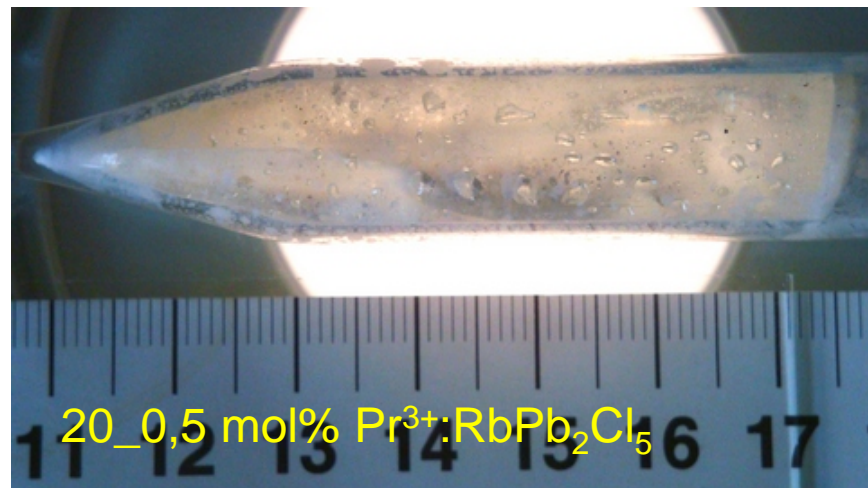
Vertical Bridgman method

- Crystal growth from the melt
- Container = **quartz ampoule**
- Two and more-section resistive furnace
 - top section – ABOVE m.p.
 - bottom section – BELOW m.p.
- Temperature gradient between sections – **10 to 50 K/cm**
- Crystal growth
 - unseeded
 - pulling ampoule down by rate **0,2 to 1,0 mm/h**
 - **10 days**
- RE elements introduced as metals
 - nomin. conc. **0.5 mol% (Yb)**
and **5 mol% (Nd, Pr)**

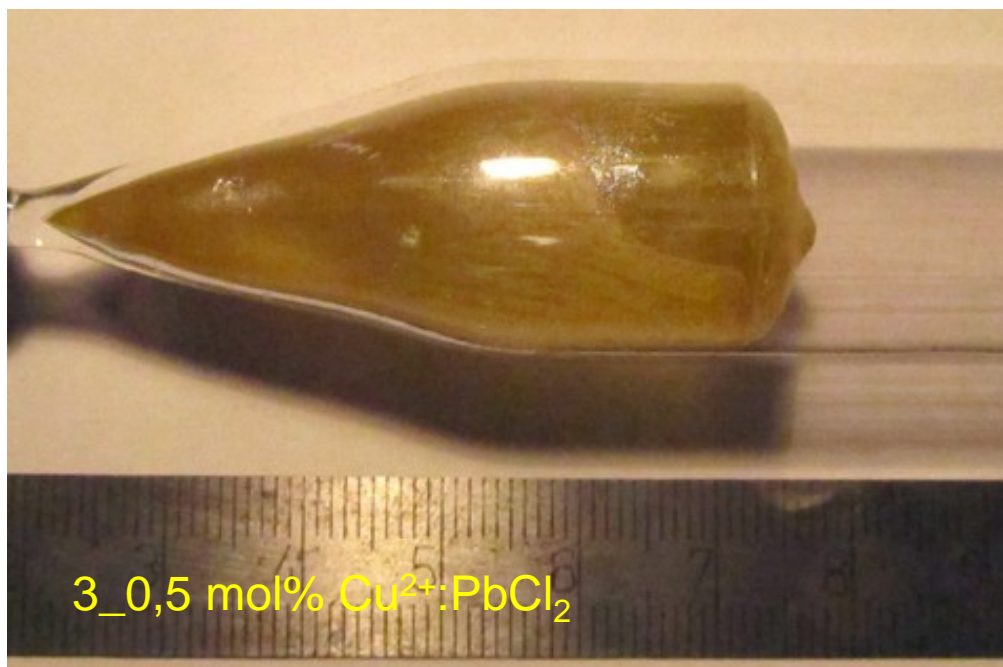




24_0,5 mol% $\text{Yb}^{3+}:\text{RbPb}_2\text{Cl}_5$



20_0,5 mol% $\text{Pr}^{3+}:\text{RbPb}_2\text{Cl}_5$



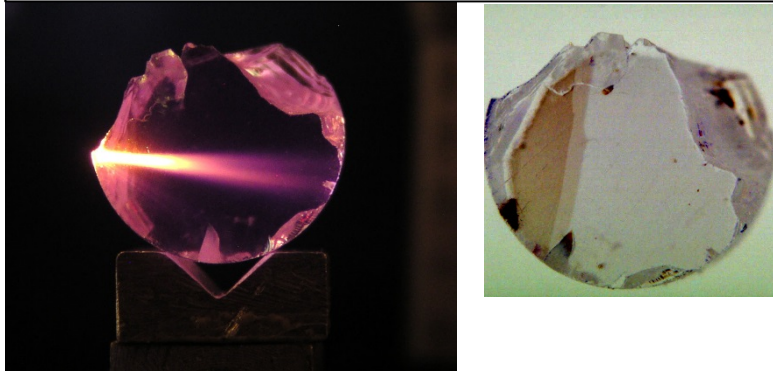
3_0,5 mol% $\text{Cu}^{2+}:\text{PbCl}_2$

Optical microscopy – crossed polar.

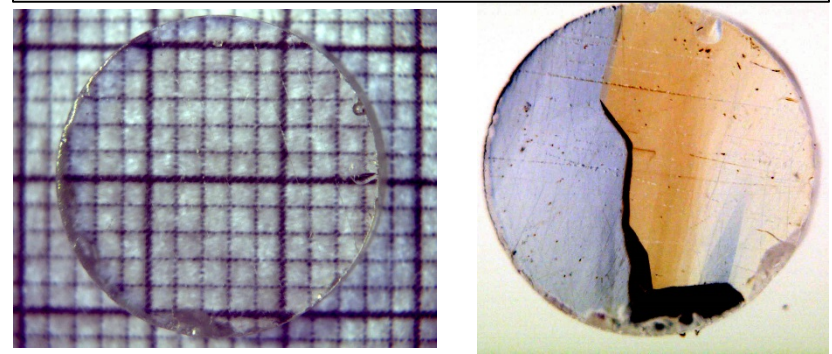
RbPb₂Cl₅

m.p. 423 C, monoclinic structure, a = 8.915 Å, b = 7.950 Å, c = 12.445 Å, beta = 90.14 deg

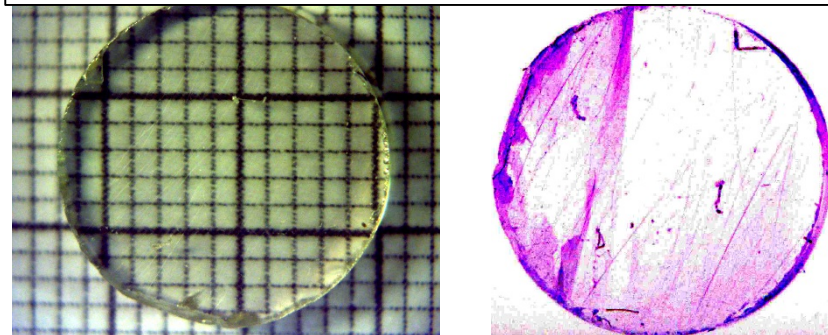
5%Nd:RbPb₂Cl₅



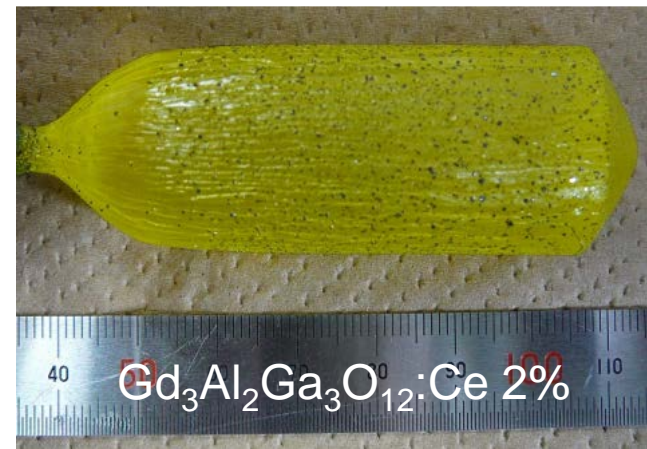
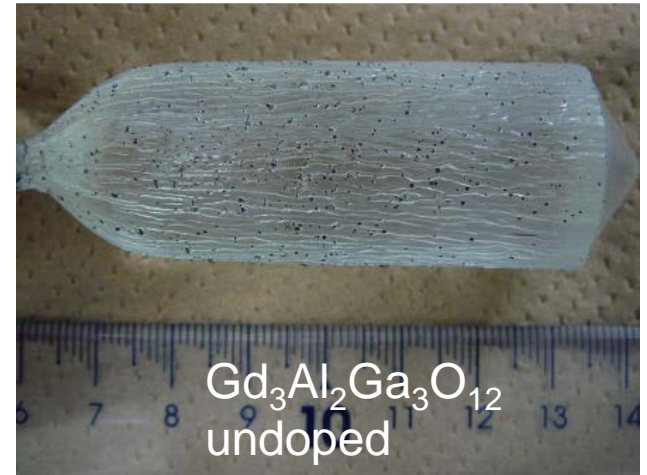
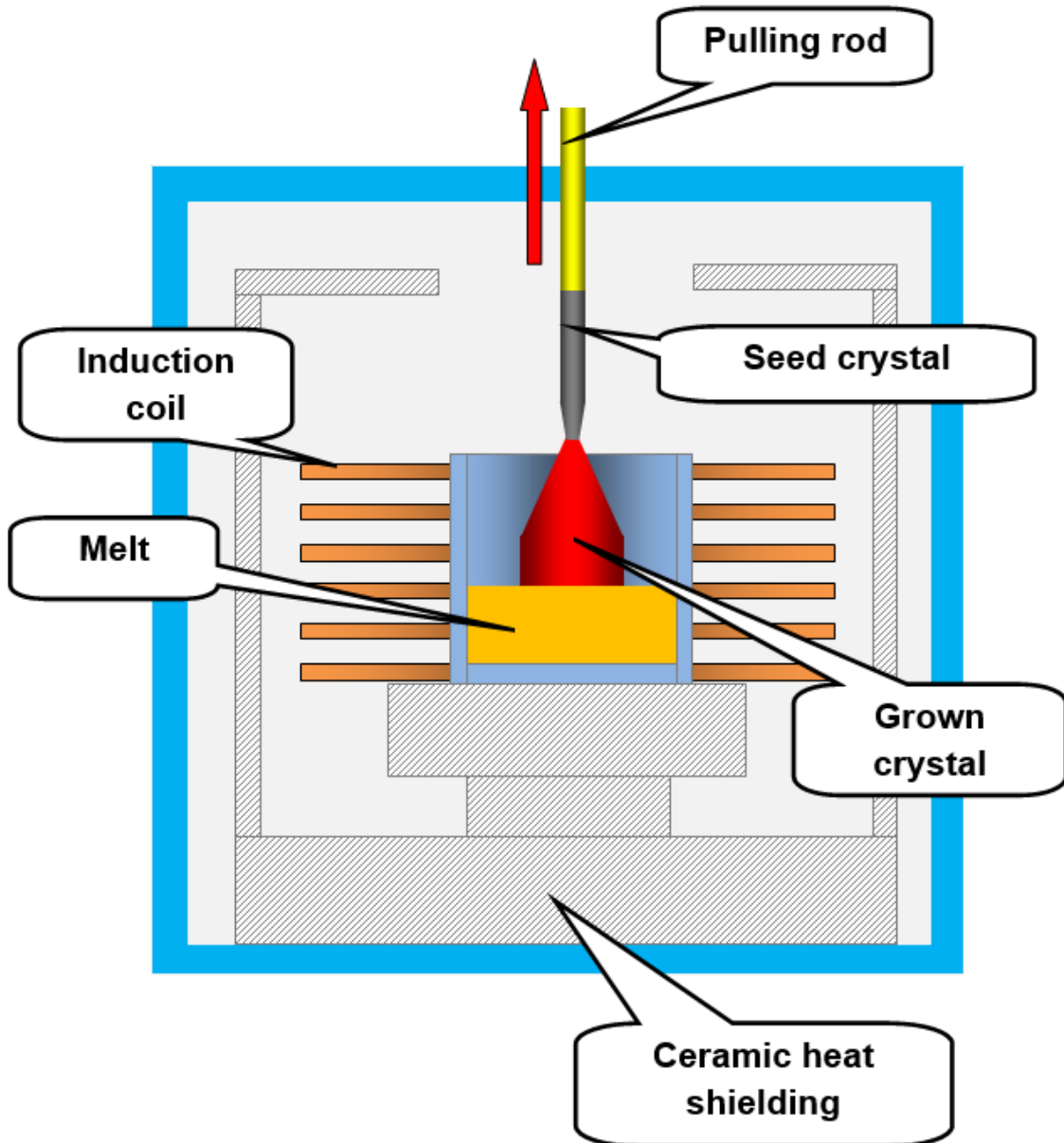
0.5%Yb:RbPb₂Cl₅



5%Pr:RbPb₂Cl₅

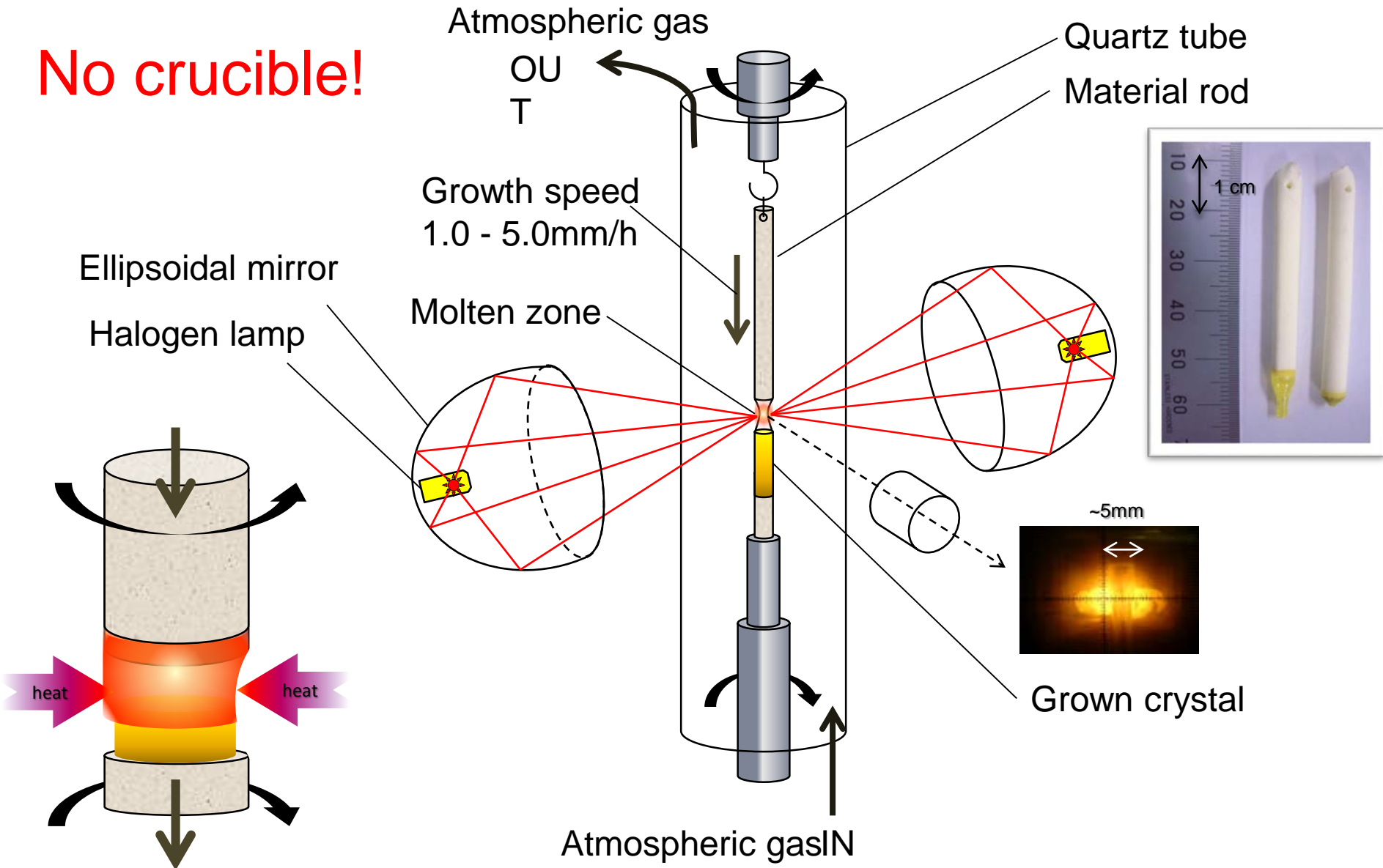


Czochralski method



Optical floating-zone (OFZ) method

No crucible!

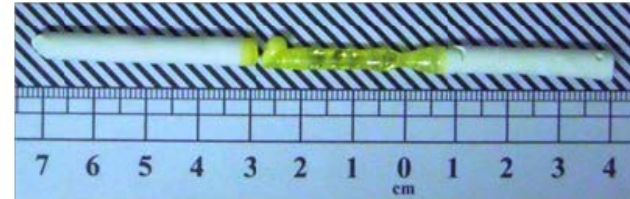


Optical floating-zone (OFZ) method

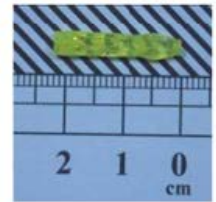


Asgal FZ-SS35WV

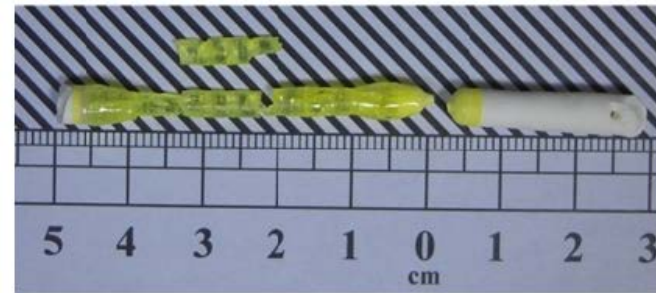
As grown crystal



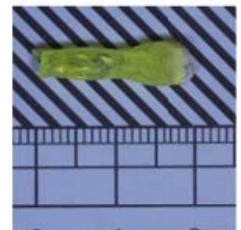
Polished



$\text{Gd}_{2.9995}\text{Ce}_{0.0005}\text{Ga}_2\text{Al}_3\text{O}_{12}$ (O_2 20%)



$\text{Gd}_{2.9995}\text{Ce}_{0.0005}\text{Ga}_2\text{Al}_3\text{O}_{12}$ (O_2 40%)



$\text{Gd}_{2.9995}\text{Ce}_{0.0005}\text{Ga}_2\text{Al}_3\text{O}_{12}$ (O_2 100%)

Optical floating-zone (OFZ) method

Composition: $(\text{Gd}_{0.995}\text{Ce}_{0.005})_3\text{Ga}_2\text{Al}_3\text{O}_{12}$

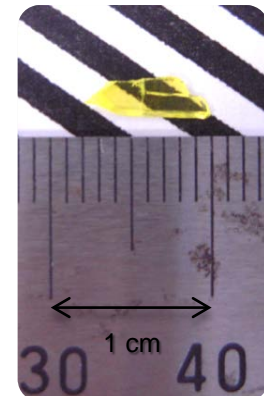
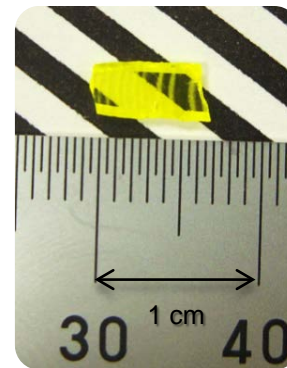
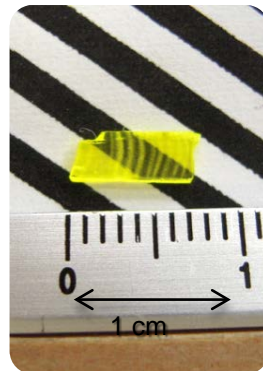
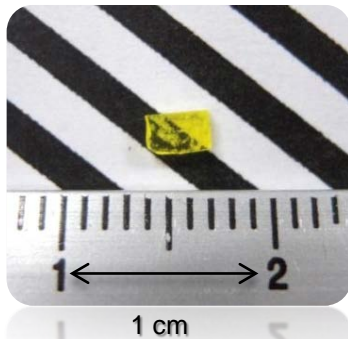
Oxygen gas

① 2 vol%

② 20 vol%

③ 40 vol%

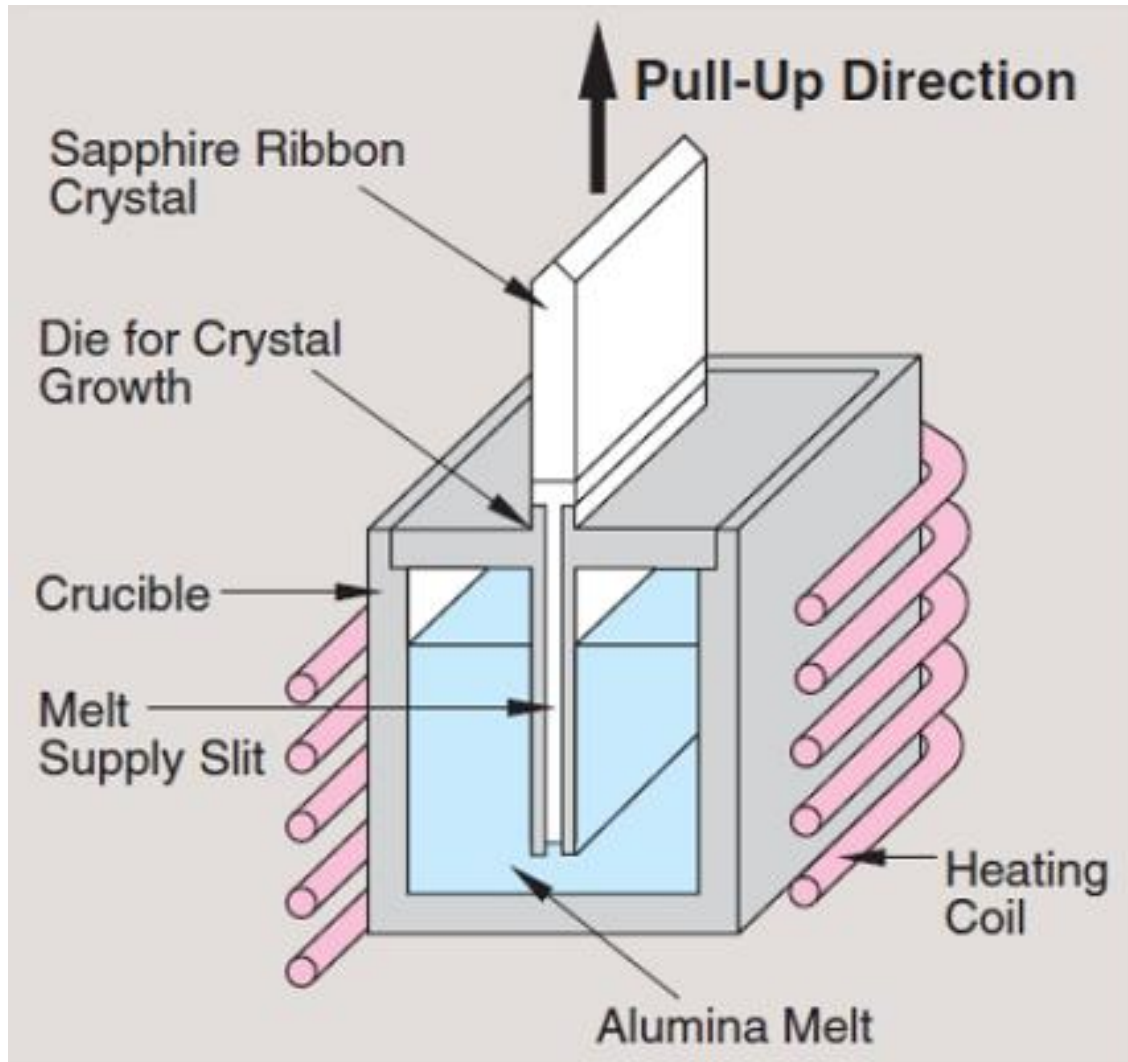
④ 100 vol%



Ar 100%

O₂ 100%

Edge-defined film-fed growth (EFG) method



From the webpage of ChinaTungsten corp.

Thank you for your attention!

Micro-pulling-down laboratory

Projects

2015-2017 Czech Science Foundation

Grant for excellent junior scientists 15-18300Y (J. Pejchal)

2018-2020 Czech Science Foundation

Standard grant 18-14789S (J. Pejchal)

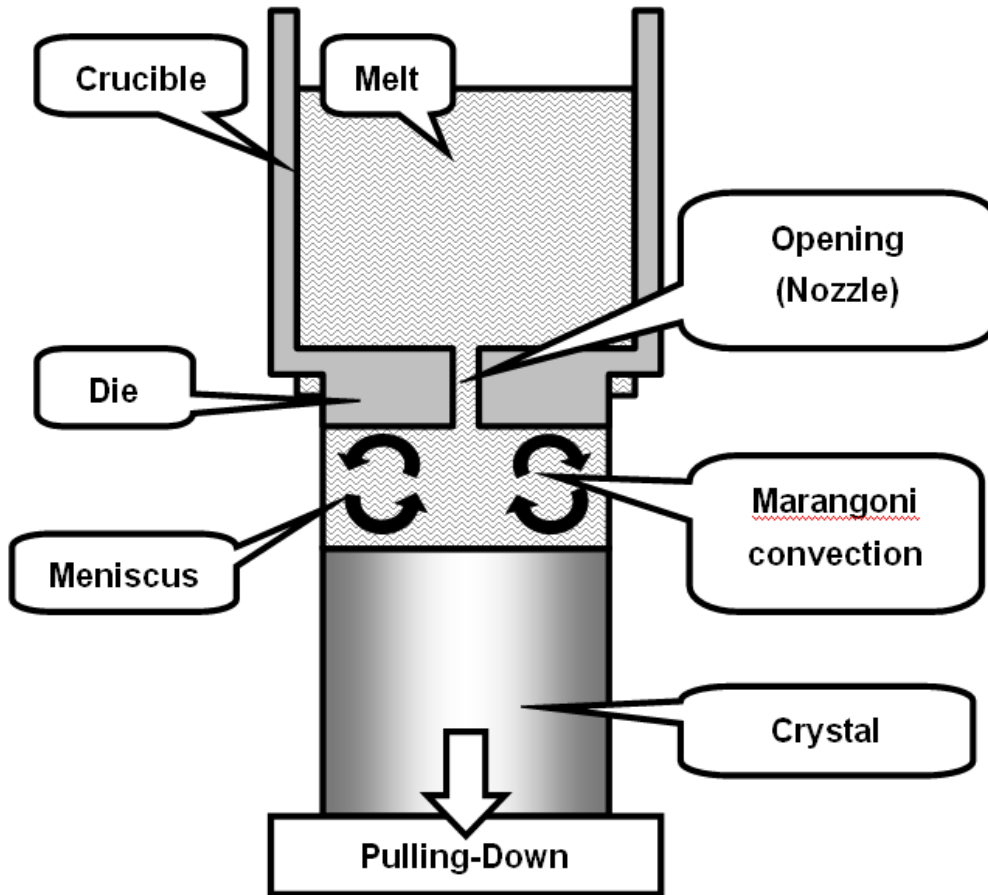
2018-2020 Czech Science Foundation

Grant for excellent junior scientists 18-17555Y (R. Král)

Close collaboration with **luminescence group** (V. Jarý, M. Nikl)
and **EPR group** (V. V. Laguta, M. Buryi)

Strong industrial background (Crytur Ltd., Nuvia Corp.)

Selected phenomena in crystal growth by mPD method



Marangoni convection – more significant than buoyancy, responsible for melt mixing in the meniscus and equilibrium between the melt and growing crystal (difference from EFG)

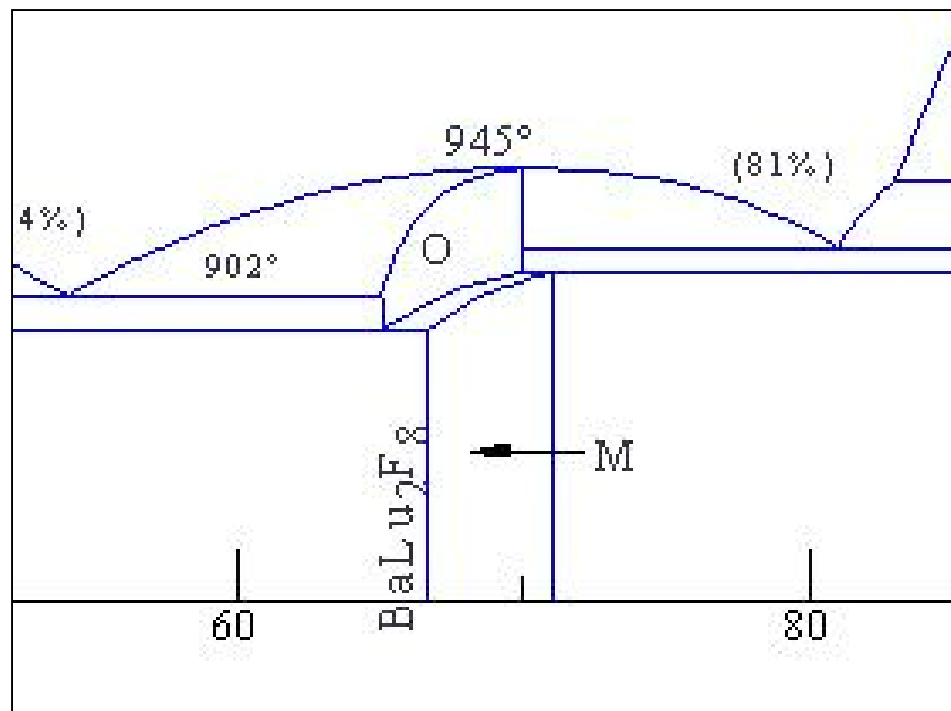
Meniscus thickness – influences Marangoni convection

Crystal/nozzle diameter ratio
– small: mass exchange with the melt in the crucible, segregation, capability of growth incongruently melting compounds
– high: fast transport through capillary, no equilibrium, no segregation, melt composition constant

Growth rate – equilibrium and segregation

Increasing the Lu-concentration: BaLu₂F₈ (BaLuF)

- Nd-doped BaLuF - candidate for VUV scintillator
- fast response (14ns decay time)-
Nd³⁺ 5d-4f VUV luminescence
- high density (7 g/cm³) –high gamma ray or X-ray stopping power
- Challenging crystal growth –
melting point 945°C, phase transition (from orthorhombic to monoclinic) at ~900°C



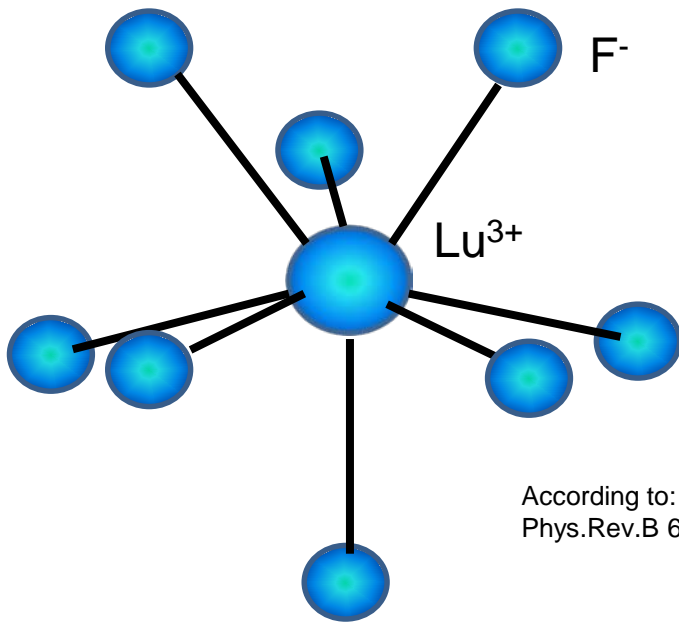
Phase diagram

According to (B.P. Sobolev, N. L. Tkachenko, *Journal of the less common Metals*, 85 (1982) 155 - 170)

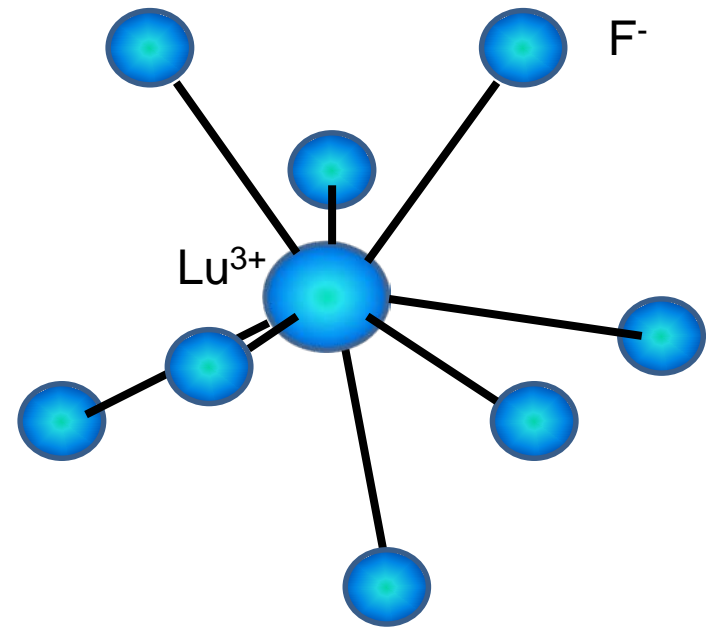
BaLu₂F₈ (BaLuF) - structure modifications

Monoclinic (low temperature) structure: C2/m space group, equivalent Lu sites – C₂ symmetry

Orthorhombic (high temperature) structure: Pnma space group, two inequivalent Lu-sites – C₁ symmetry



Lu³⁺ site 1 – “spherical”



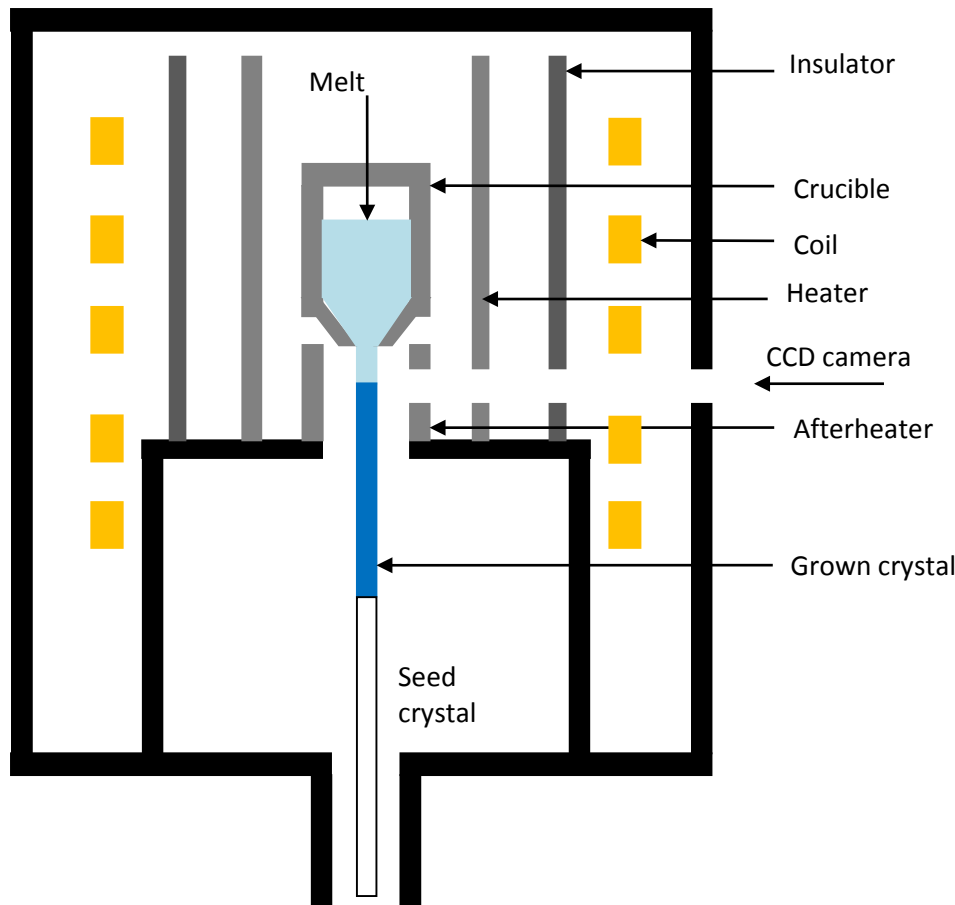
Lu³⁺ site 2 – distorted

According to: O.S. Wenger et al.
Phys.Rev.B 61 (2000) 16530

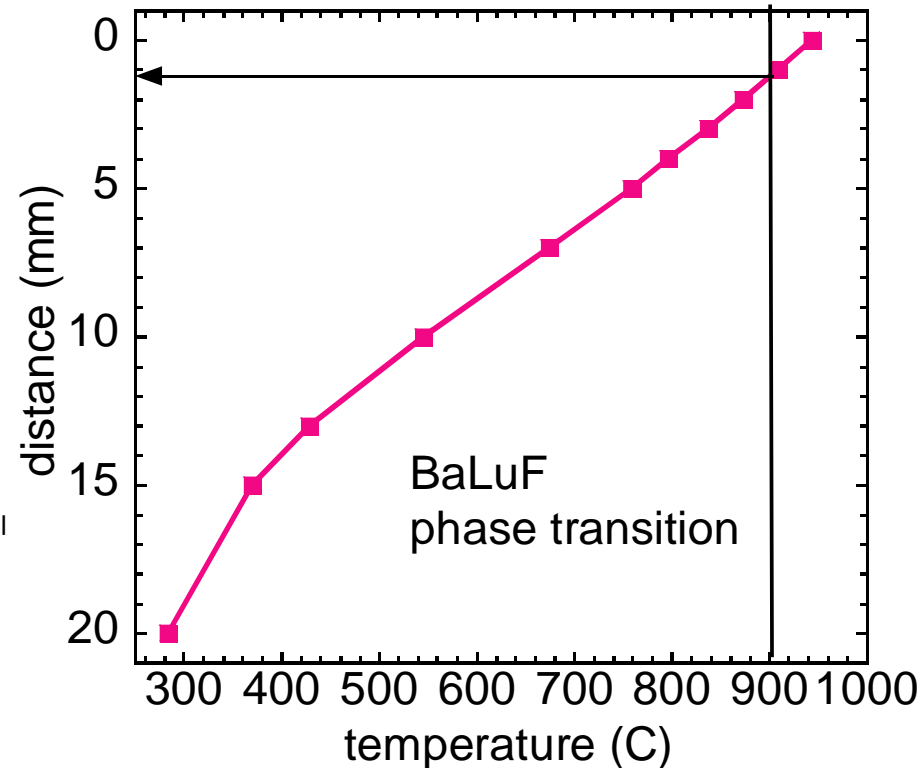
Orthorhombic phase – **two different sites for doping rare-earth ions**

Crystal growth of **monoclinic** (low temperature) BaLu_2F_8

Standard hot-zone, standard crucible



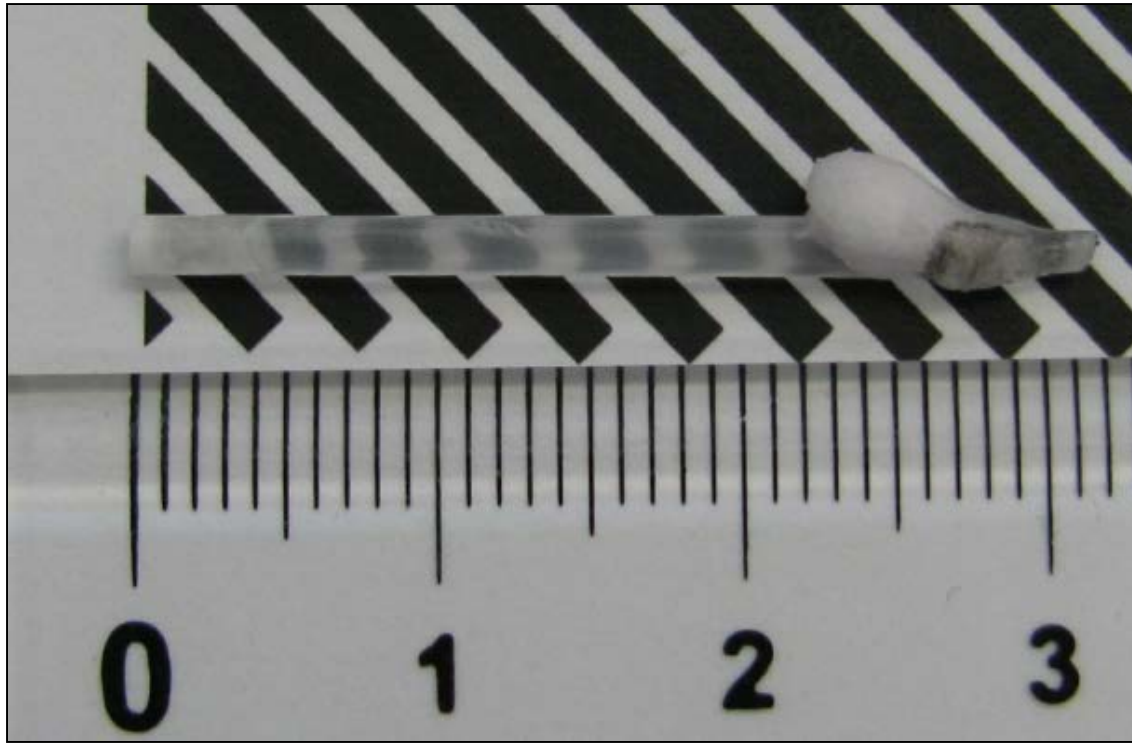
Temperature gradient



Measurement with **Pt-PtRh** thermocouple instead of seed, **starting from crucible nozzle**

Phase transition temperature measured ~ 1 mm below nozzle – cracky crystal \rightarrow **slight melting temperature reduction necessary**
 \rightarrow **LiF flux**

Crystal growth of **monoclinic** BaLu_2F_8



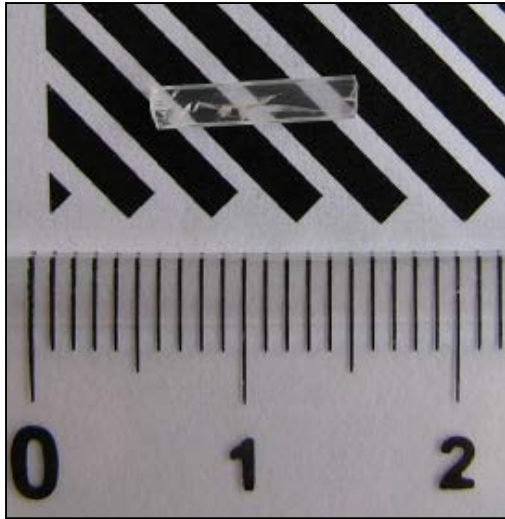
As-grown $\text{BaLu}_2\text{F}_8:\text{Nd}1\%$

10 mol% LiF flux sufficient to lower the melting point under phase transition.

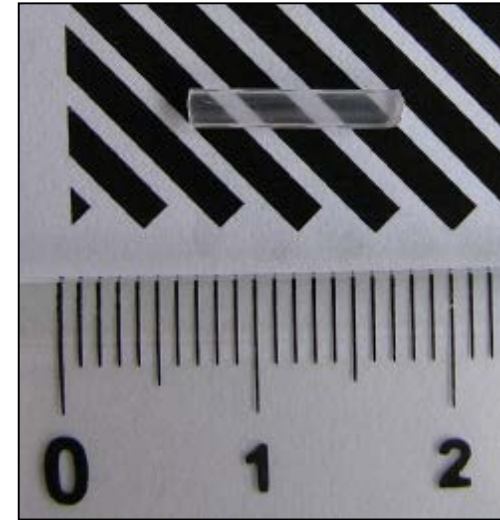
BaY_2F_8 seed. **Monoclinic BaLu_2F_8 phase confirmed by XRD.**

Samples prepared: **BaLu_2F_8** Undoped, Nd1%, Tm1%, codoped Tm1%Nd1% (to test possible $\text{Tm}^{3+} \rightarrow \text{Nd}^{3+}$ energy transfer)

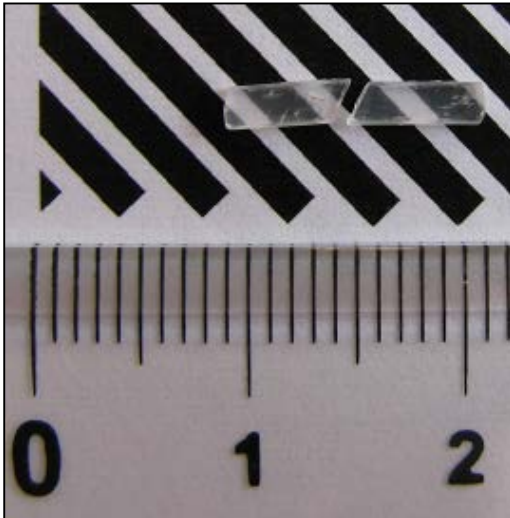
Samples of monoclinic (low temperature) BaLu_2F_8 after cutting and polishing



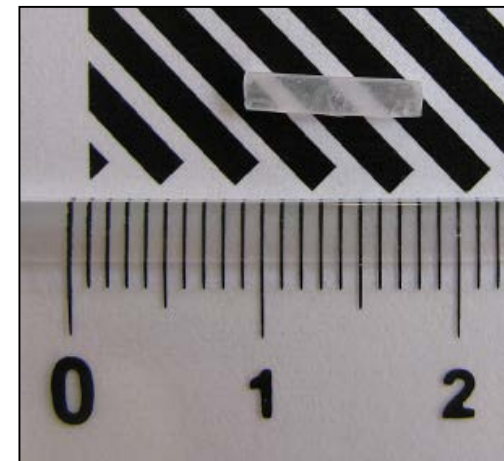
BaLu_2F_8 undoped



$\text{BaLu}_2\text{F}_8:\text{Nd}1\%$



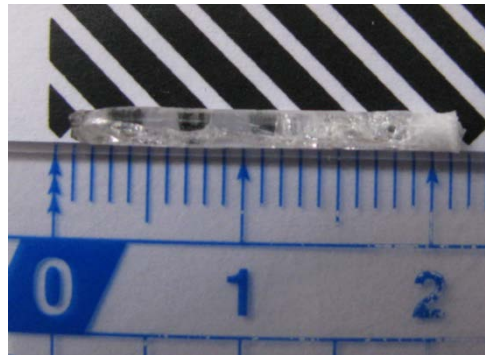
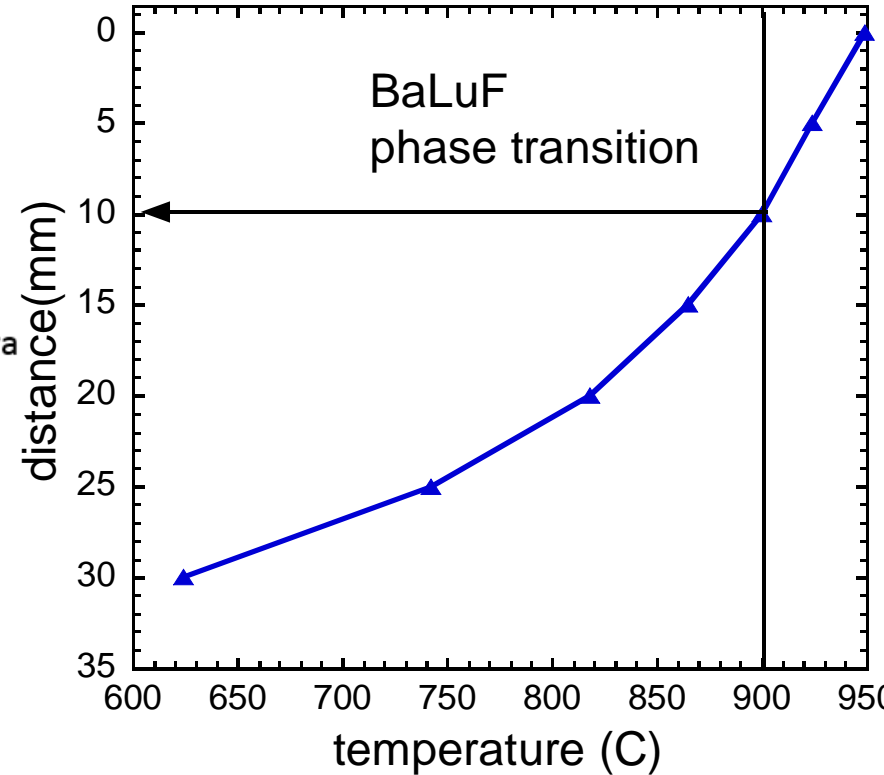
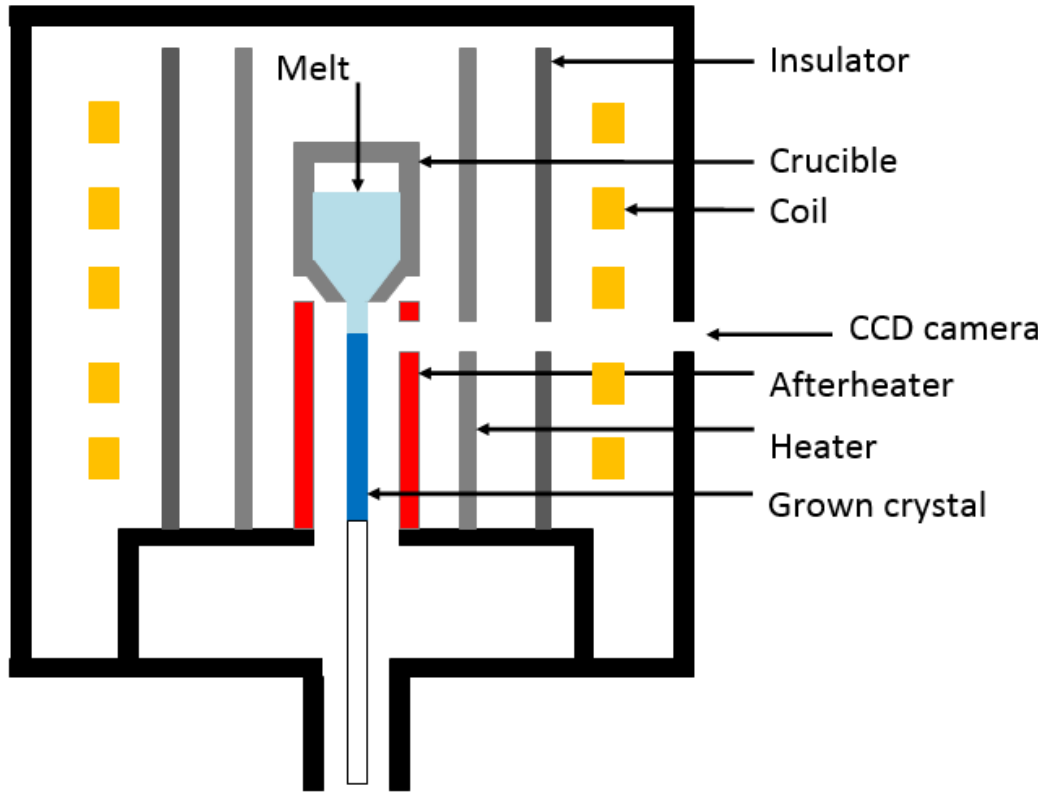
$\text{BaLu}_2\text{F}_8:\text{Tm}1\%$



$\text{BaLu}_2\text{F}_8:\text{Tm}1\%\text{Nd}1\%$

Crystal growth of **orthorhombic** (high temperature) BaLu_2F_8

Hot zone search

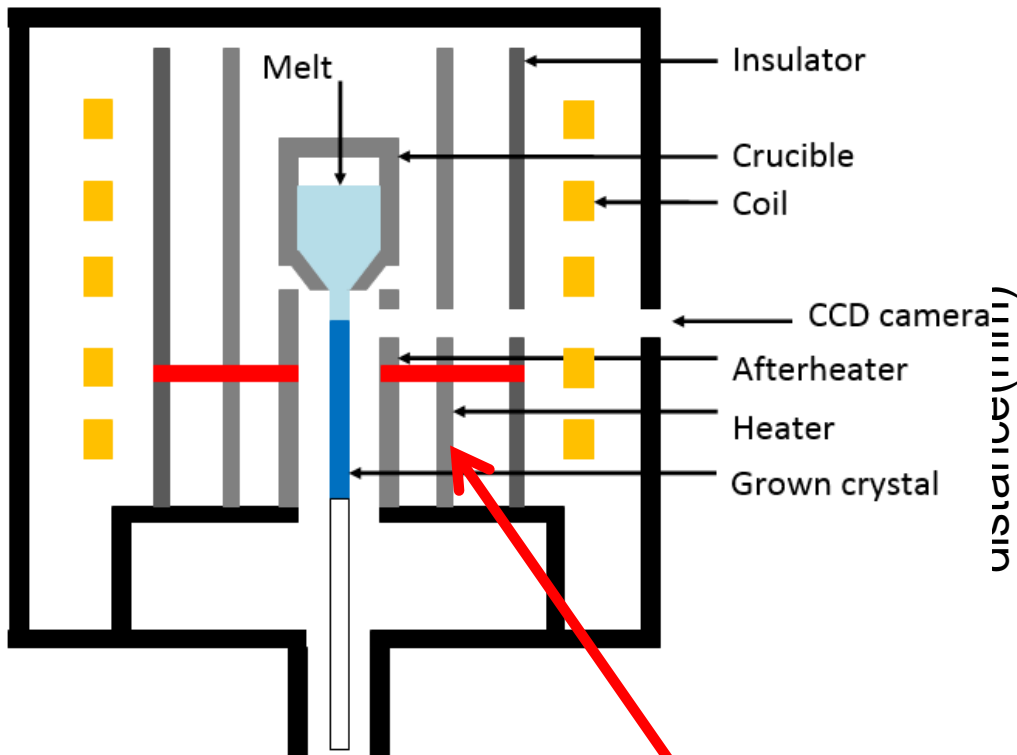


Long hot zone with **long 40mm afterheater** – not suitable due to high probability of melt drop, **quenching process** – **partial success**

Crystal growth of **orthorhombic** (high temperature) BaLu_2F_8

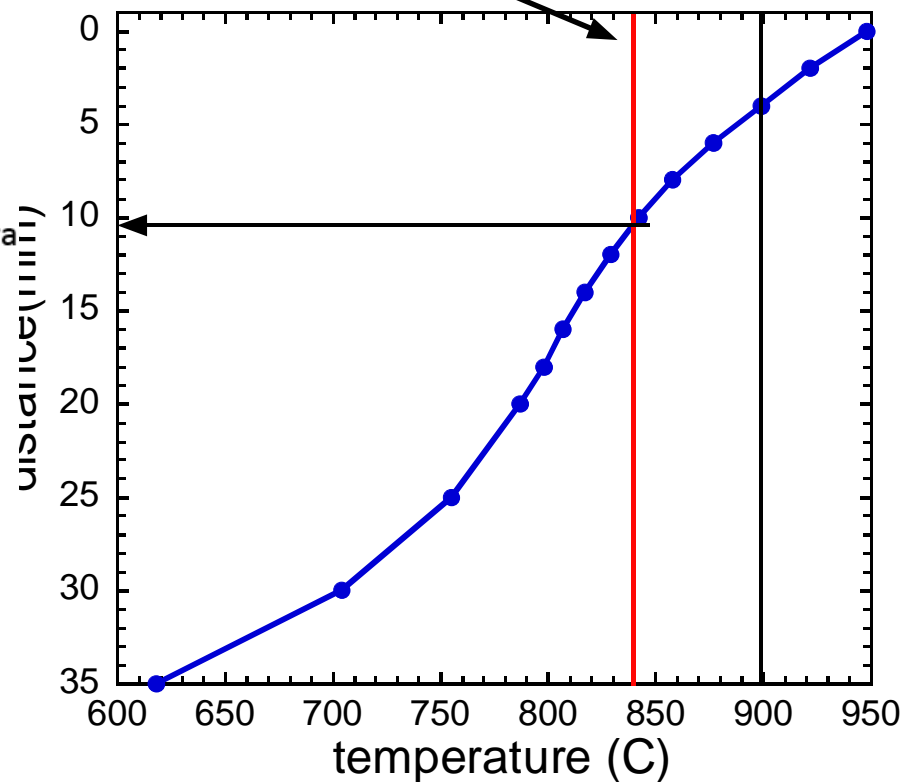
Hot zone search

BaLuF phase transition



Porous insulating carbon

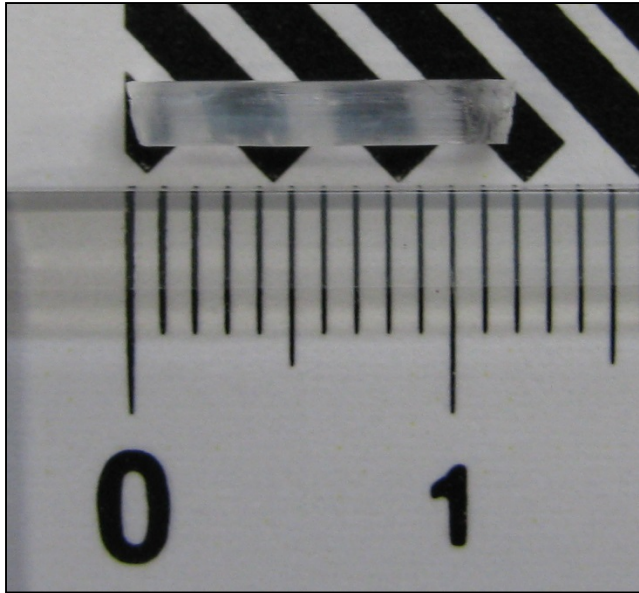
"Real" phase transition



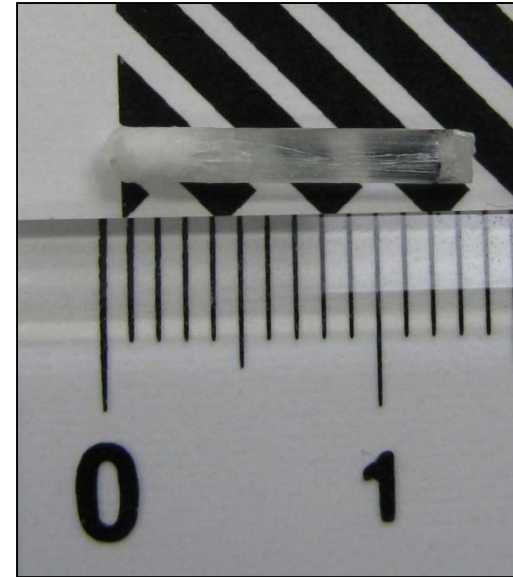
Regular hot zone with **"afterzone"** – suitable to grow around 10-15 mm crystals.

Phase transition occurs at distances higher than expected. **Heat conduction through growing crystal significant.** **Quenching process** applied

Crystal growth of orthorhombic BaLuF



As-grown crystal of orthorhombic
BaLu₂F₈:Nd1%



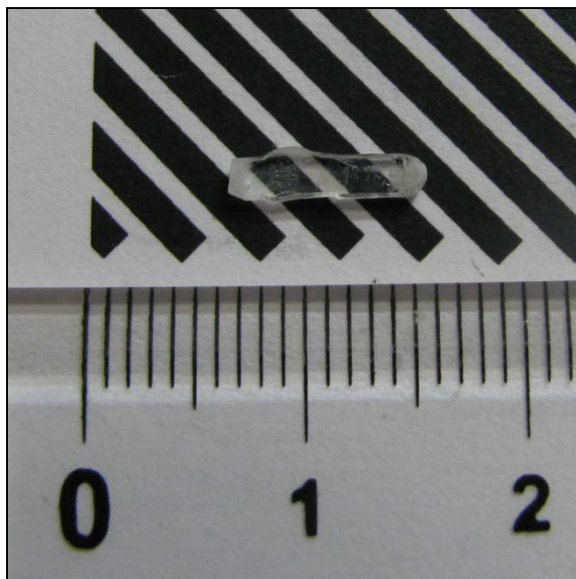
As-grown crystal of orthorhombic
BaLu₂F₈:Tm1%

Orthorhombic phase confirmed by XRD (signs of monoclinic phase also detected)

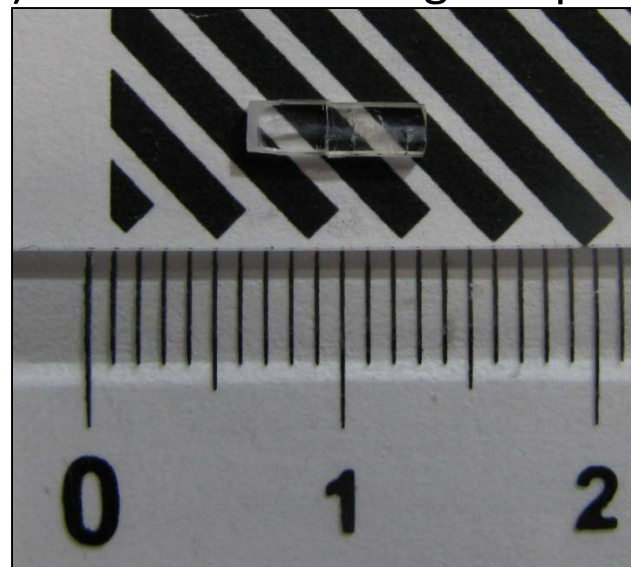
Samples prepared: **BaLu₂F₈** Undoped, Nd1%, Tm1%

codoped Tm1%Nd1% (to test possible Tm³⁺ → Nd³⁺ energy transfer in
the host with inequivalent Lu³⁺ sites)

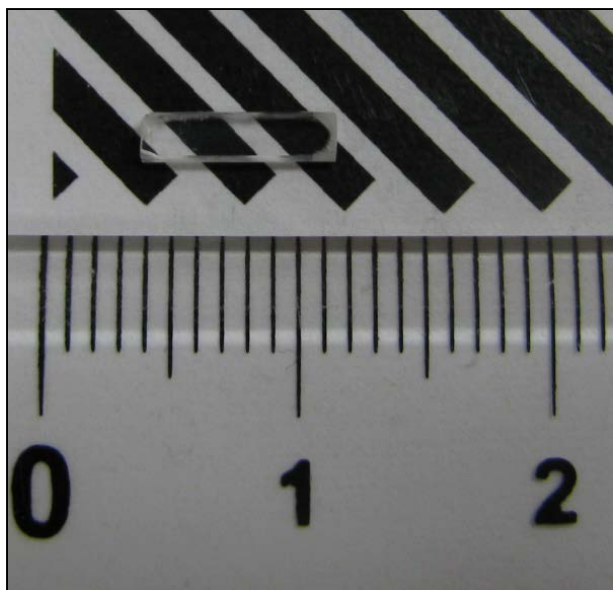
Samples of orthorhombic (high temperature) BaLuF after cutting and polishing



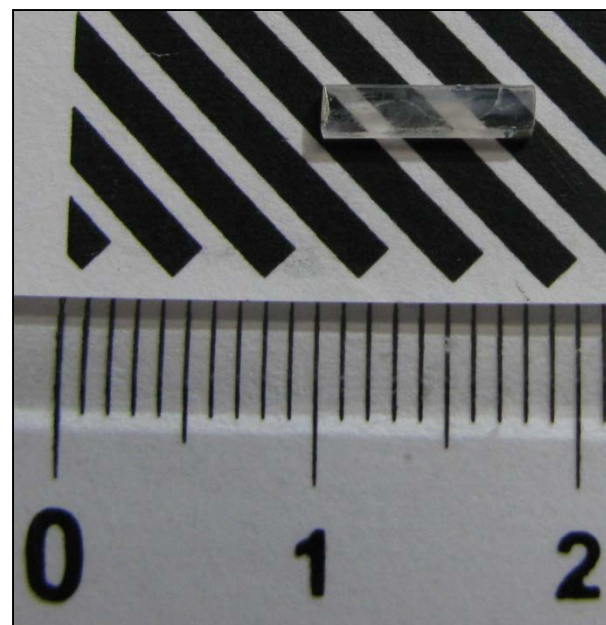
BaLu₂F₈ undoped



BaLu₂F₈:Nd1%



BaLu₂F₈:Tm1%



BaLu₂F₈:Tm1%Nd1%